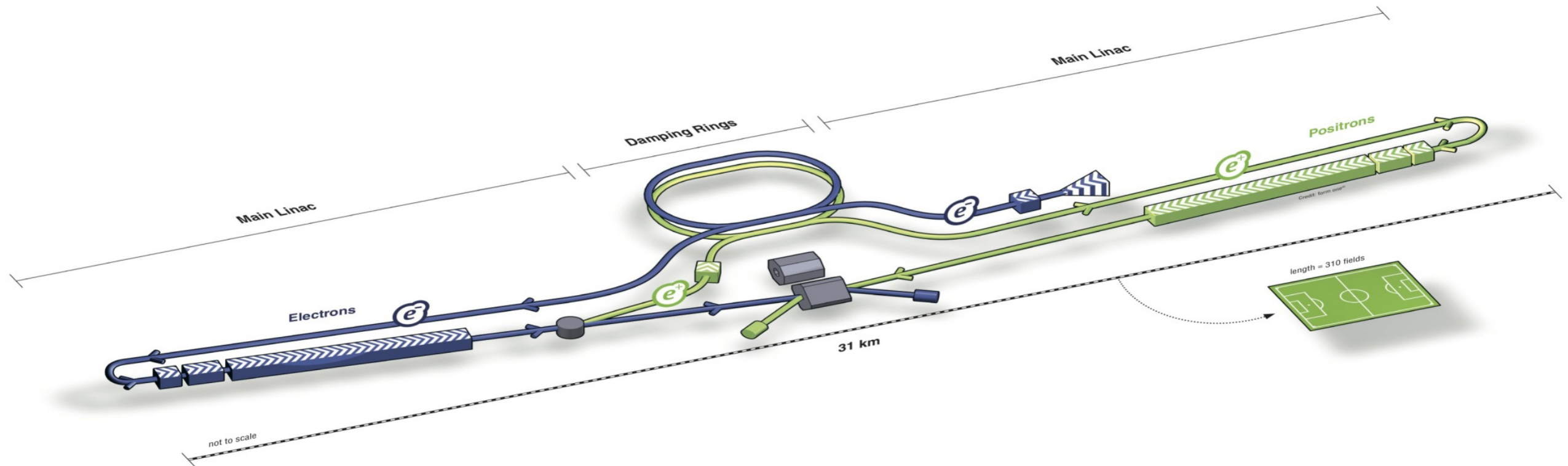


SOI pixel detector for the ILC experiment

Mini workshop on SOIPIX at IHEP 2016/7/14

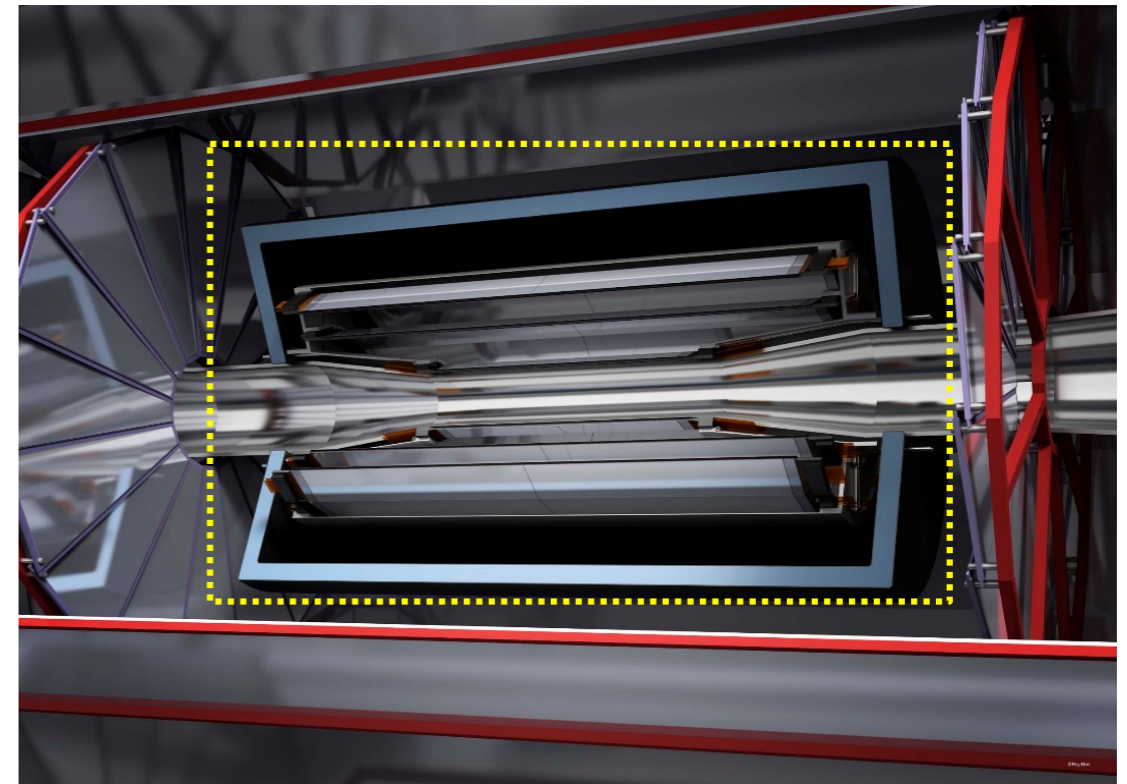
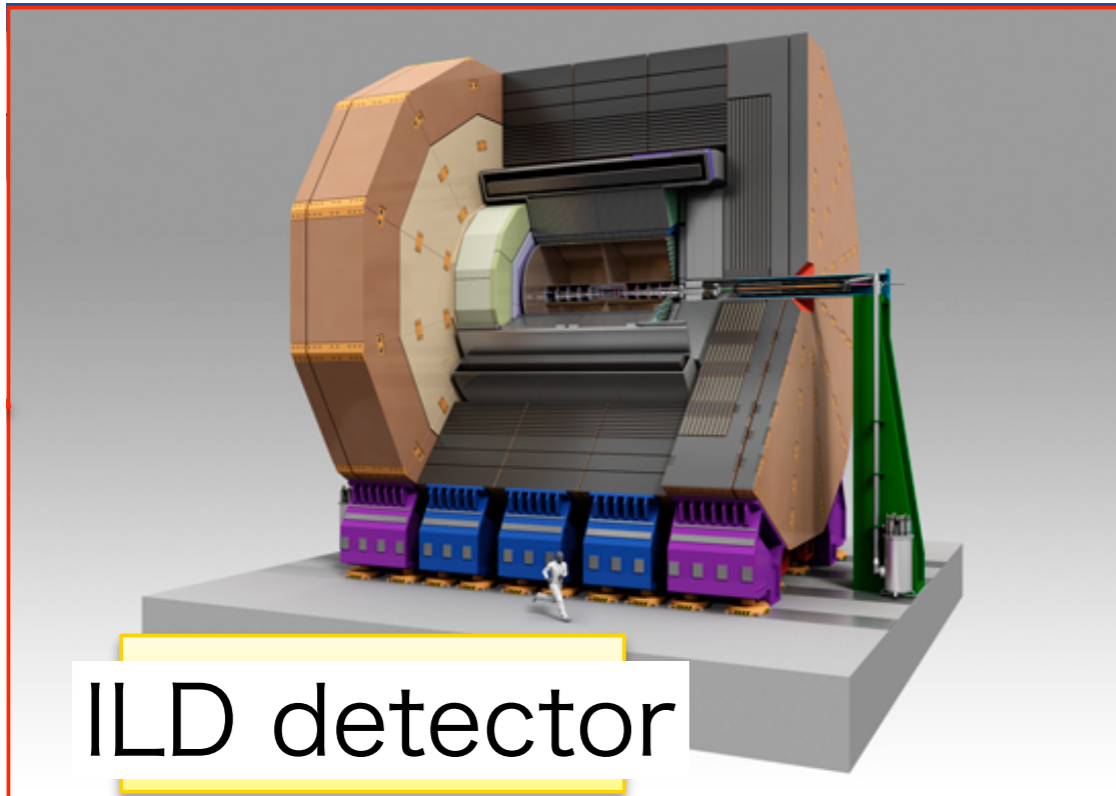
Osaka University Manabu Togawa

ILC experiment

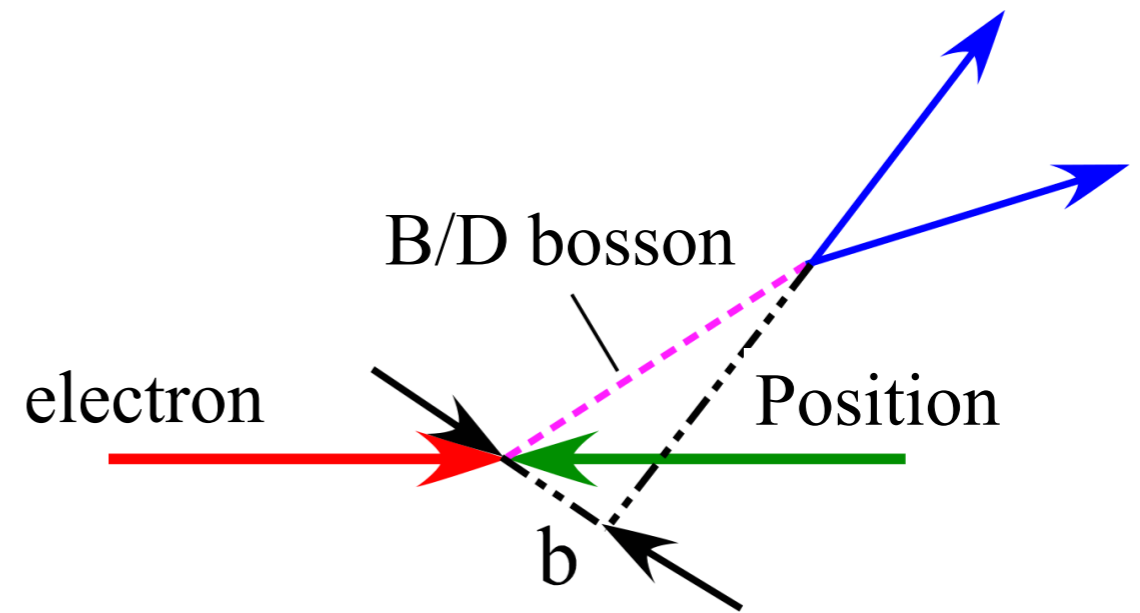


- $e^+ e^-$ collider of $\sqrt{s} = 250 - 500$ GeV
- Precise measurement of Higgs particle
- Discovery of new particles
 - SUSY, dark matter...

ILC vertex detector

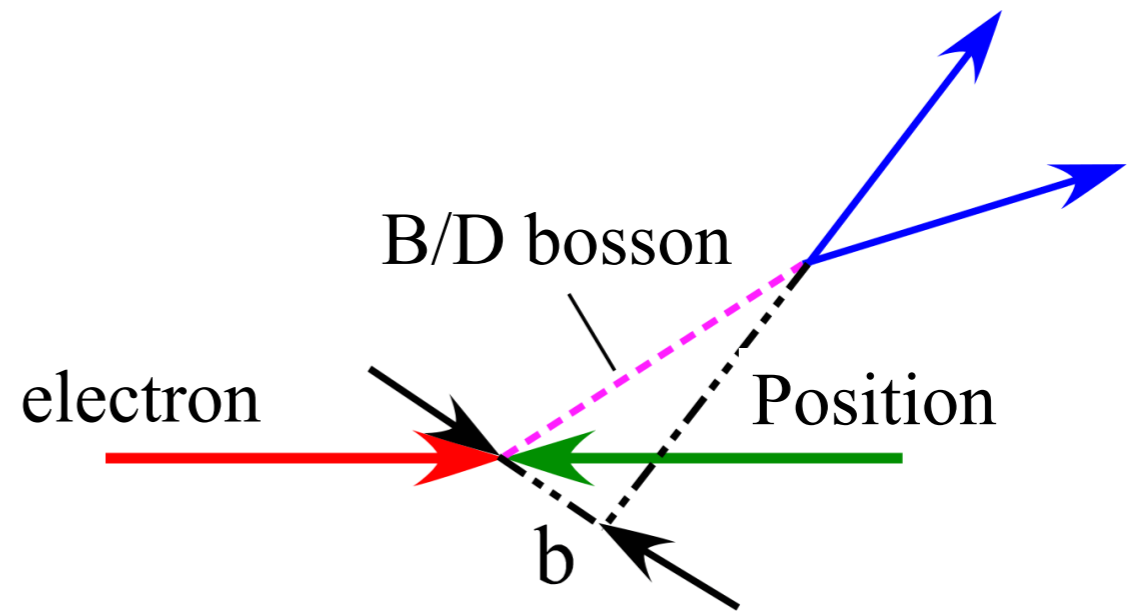


- Si pixel sensor locates around the IP point to measure the tracking of charged particles precisely.



$$\sigma_{ip} = 5\mu m \oplus 10\mu m / p \sin^{3/2} \theta$$

Requirements for ILC physics and operation



$$\sigma_{ip} = 5\mu\text{m} \oplus 10\mu\text{m} / p \sin^{3/2} \theta$$

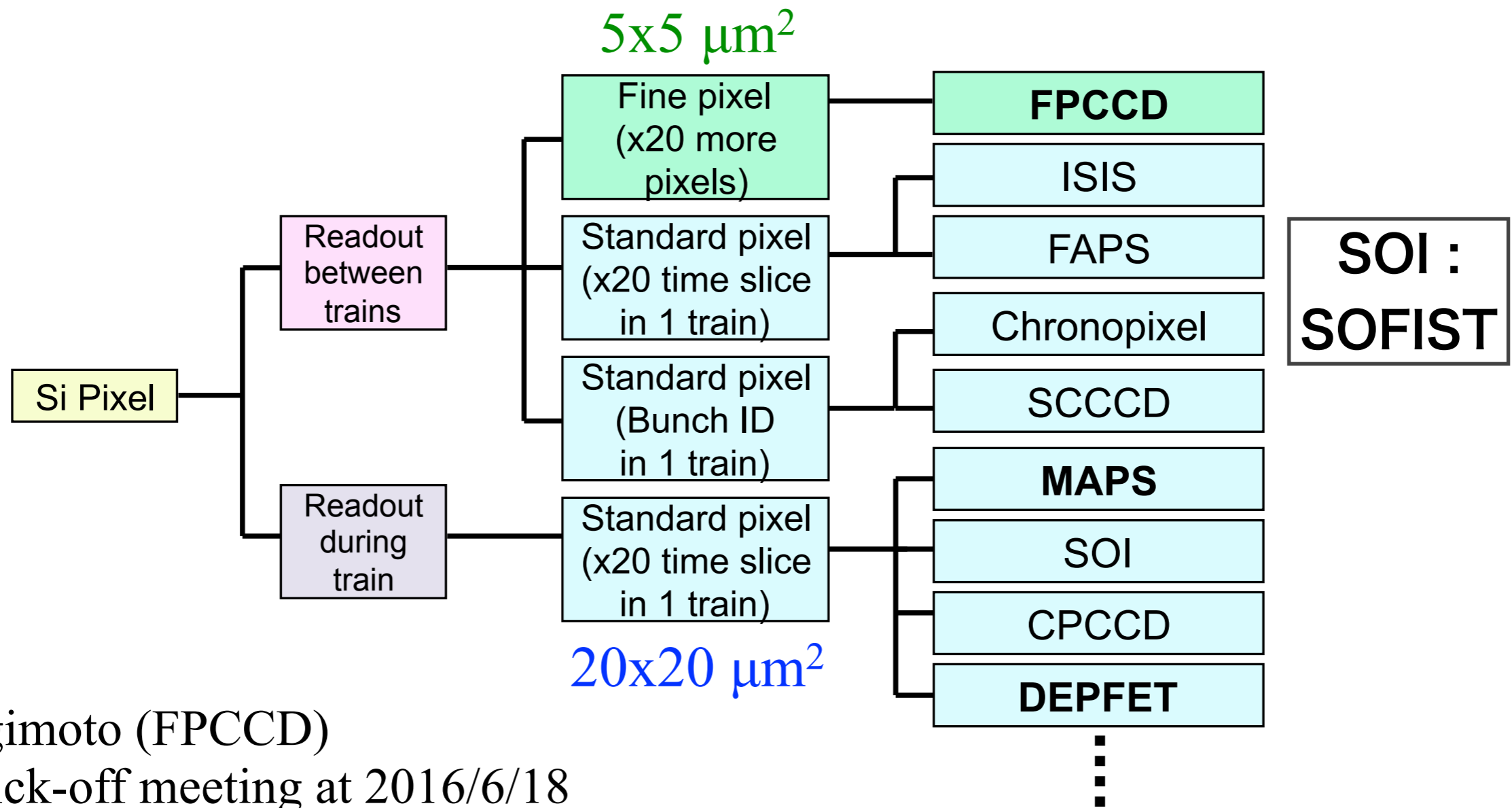
- 1) Vertex resolution
 - Position resolution : $< 3 \mu\text{m}$
 - Low material : $< 0.1\% X_0$ ($< 100 \mu\text{m}$ thickness for silicon)
- 2) Integration during beam train
 - Detector occupancy : $< 2 \%$

Beam bunch structure



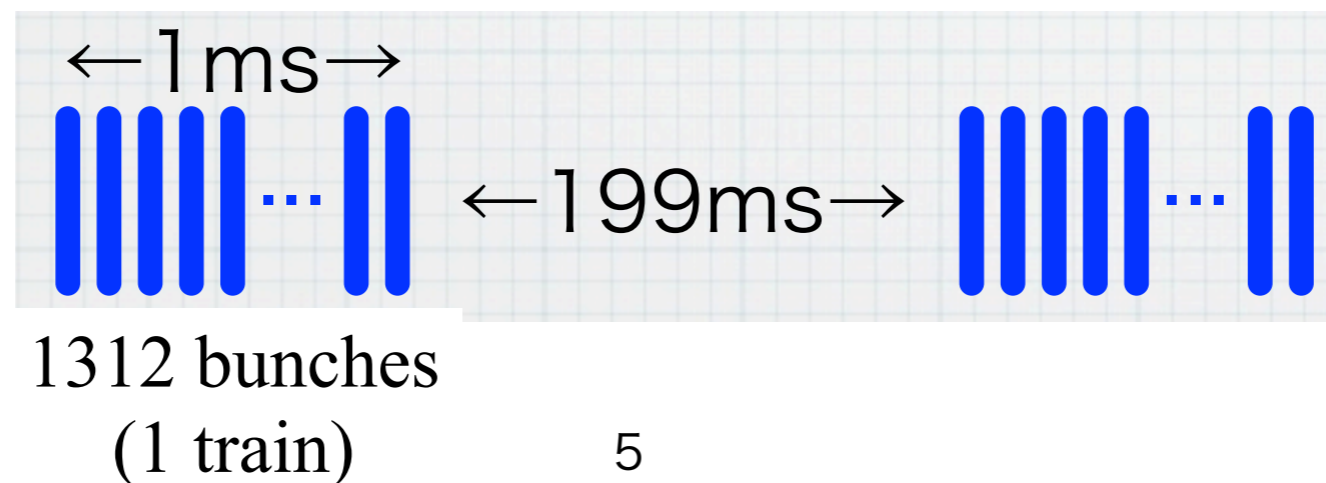
Candidates

* Hybrid type is disaster in terms of cost and amount of material



Y. Sugimoto (FPCCD)

ILC kick-off meeting at 2016/6/18



Requirement of readout ; Occupancy < 2%

Occupancy estimation on 1 train at 500 GeV for FPCCD (5x5 μm^2)

Scale to std. pixel (20 x 20 μm^2)

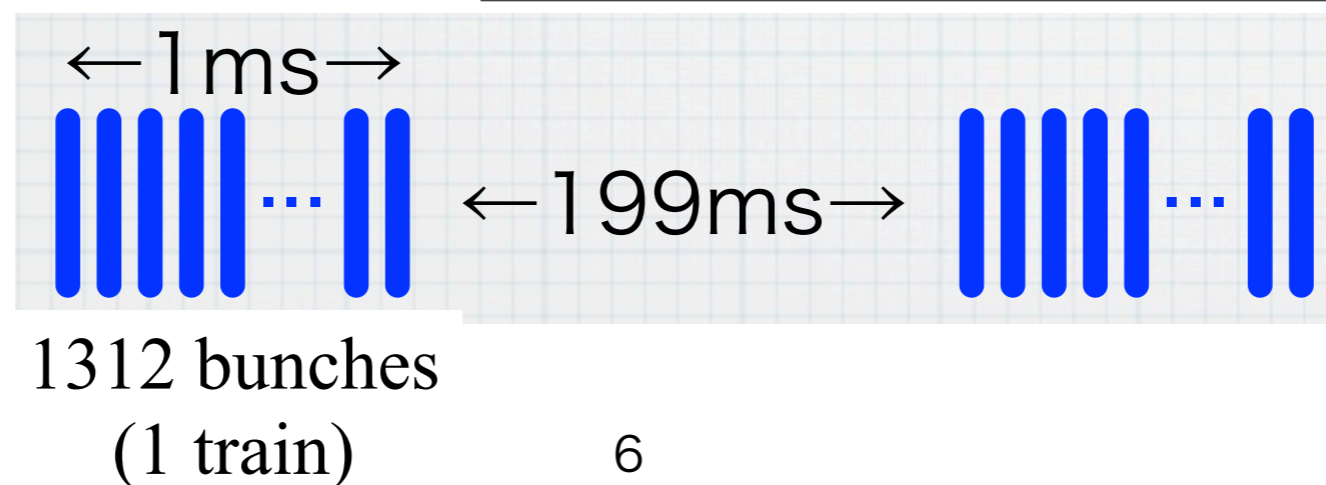
Layer	Occupancy (%)
0	1.24
1	0.78
2	0.12
3	0.10



~ 20 % (x16)

Need to have multiple readout during train or bunch identification

Beam bunch structure

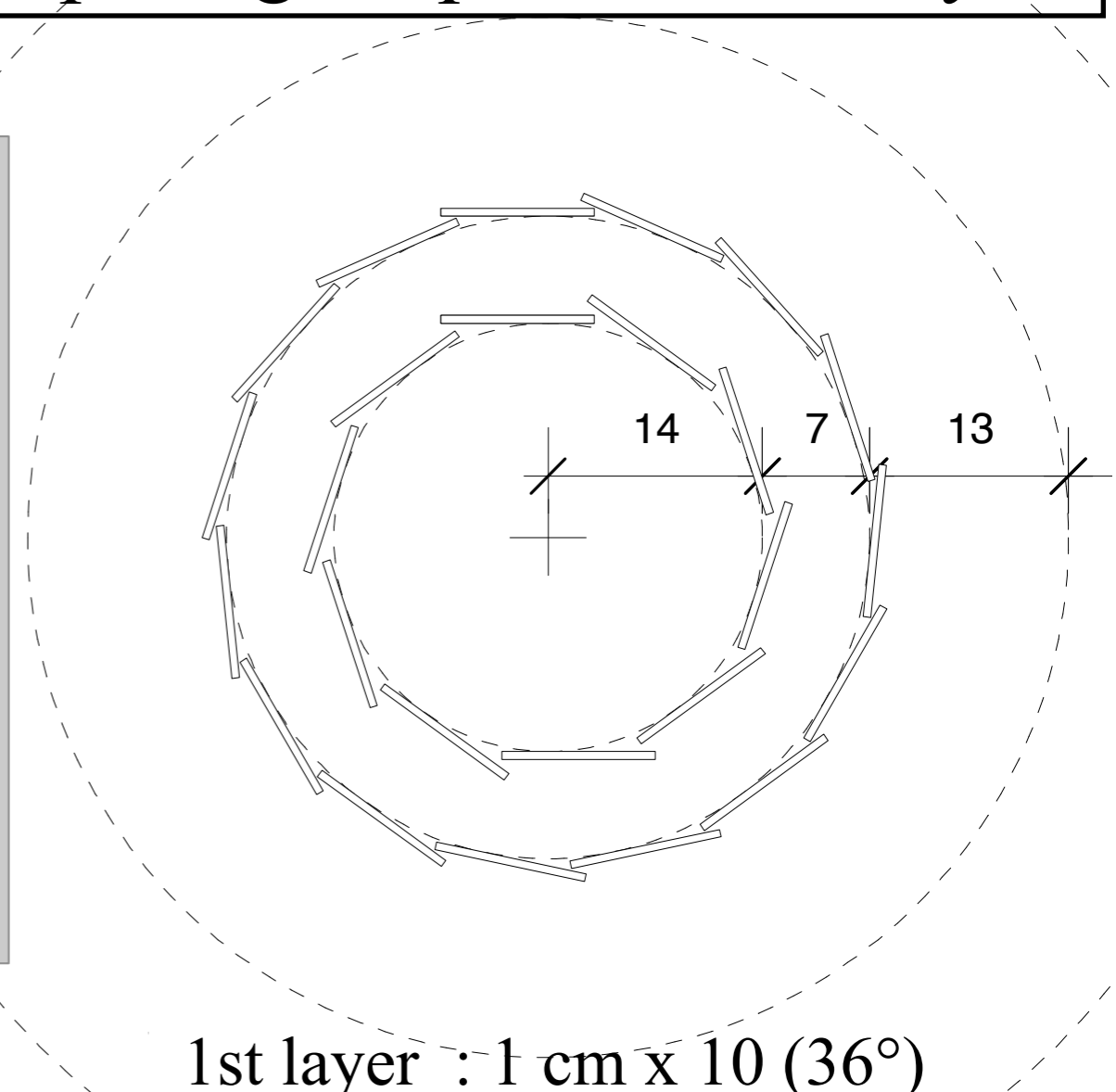
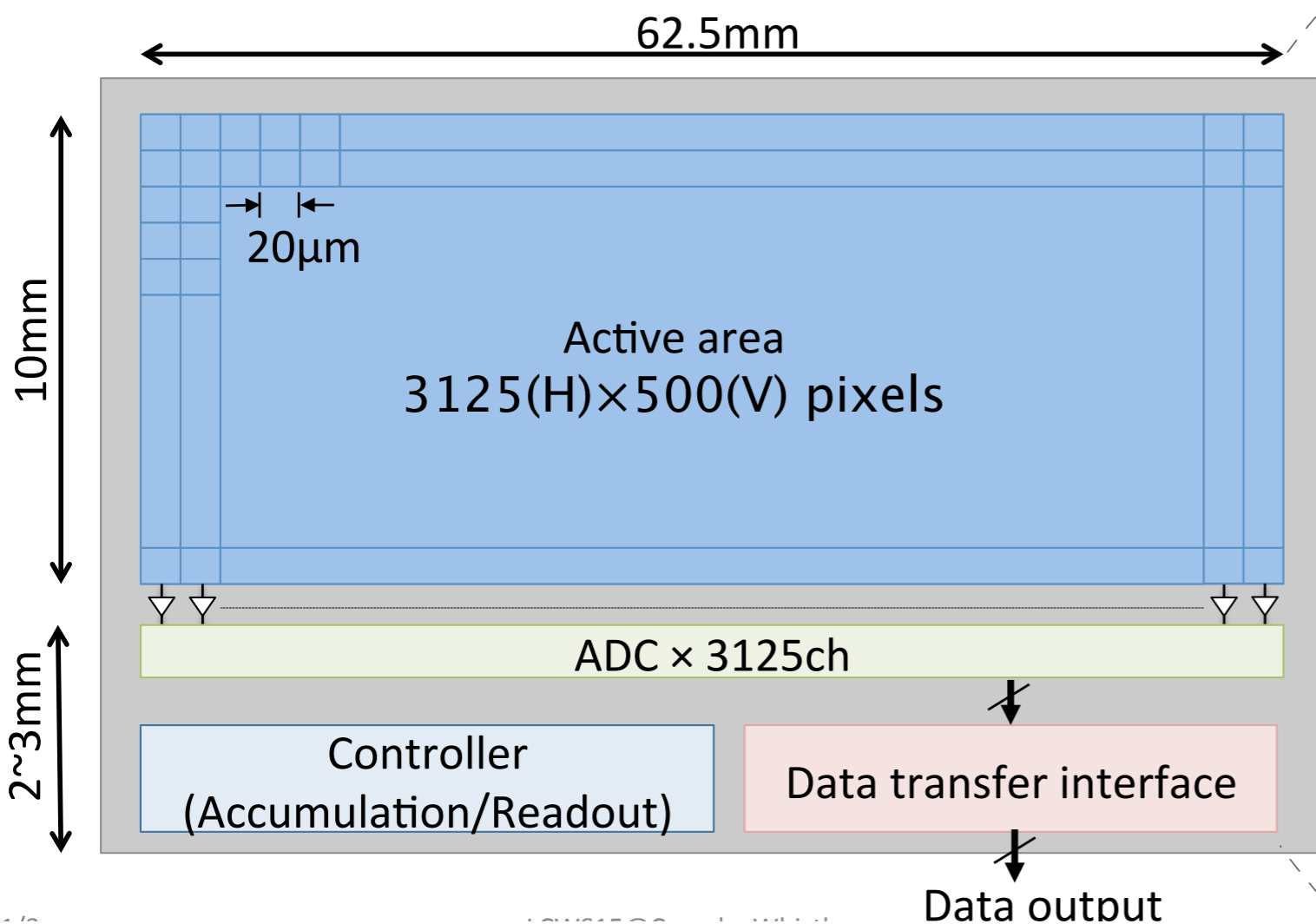


SOFIST

(SOI sensor for Fine measurements of Space and Time)

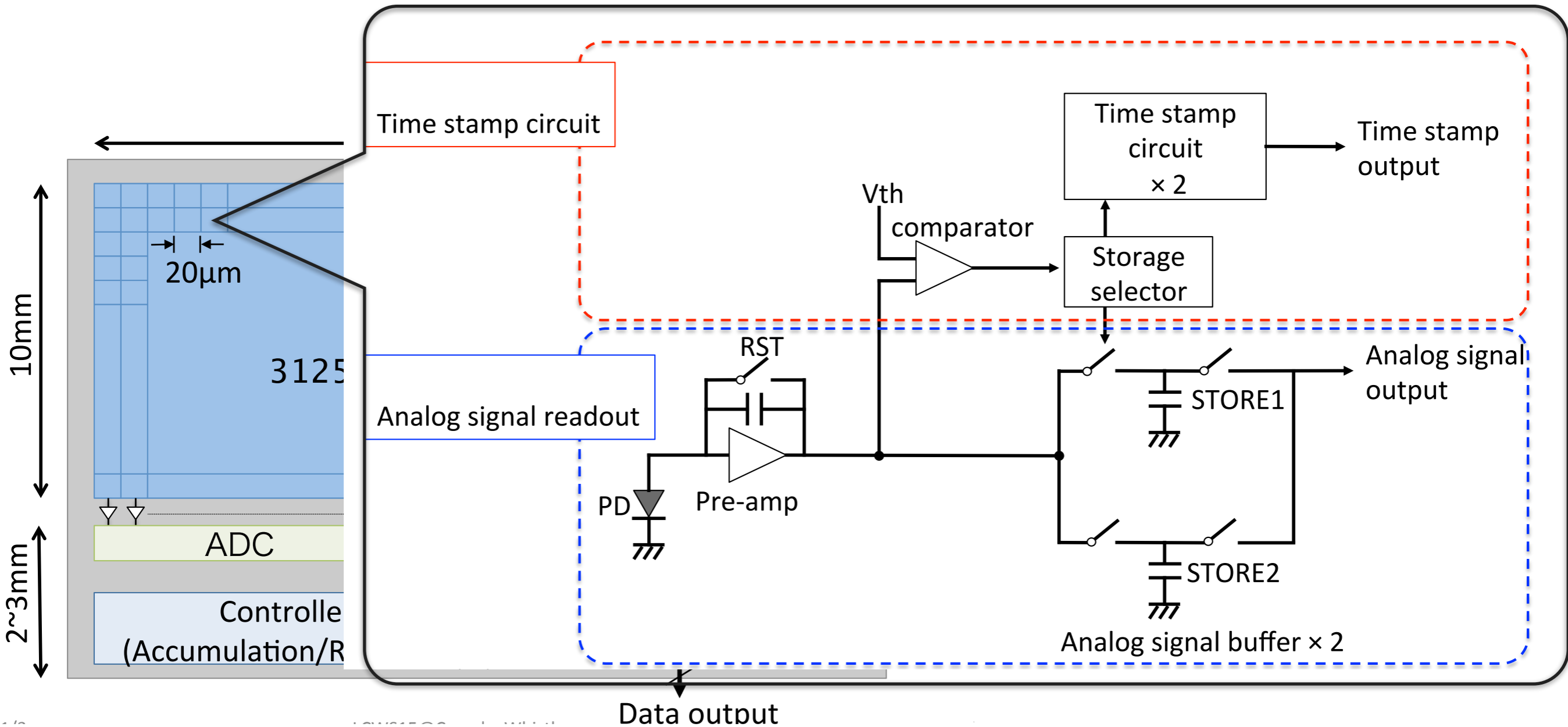
Final design

Proposing shape for inner layers



Pixel size = 20 x 20 µm²
Thickness = 50 µm

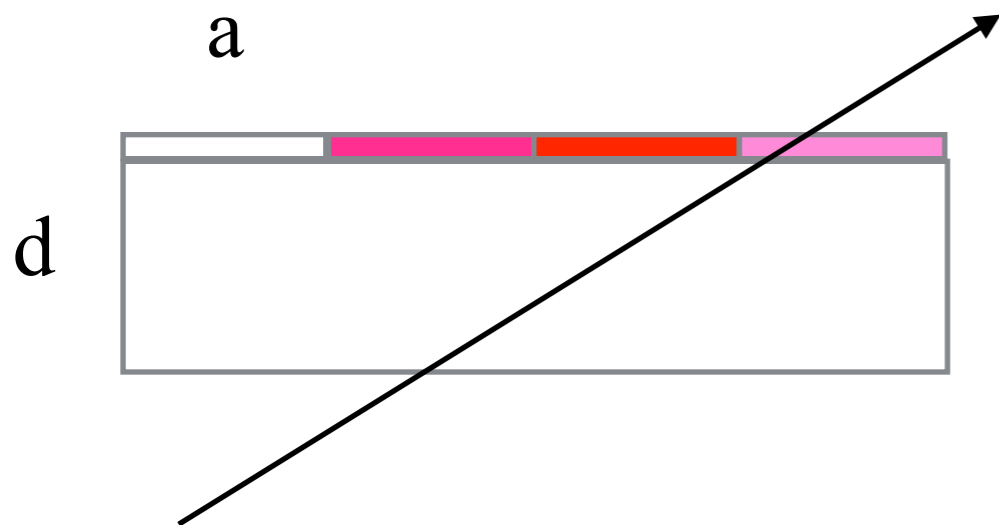
Circuit on 1 pixel (in design)



The number of buffers should be decided in terms of the occupancy

Position resolution (estimation)

Position is calculated by
centroid-method.



a : pixel pitch = 20 μm

d : thickness = 50 μm

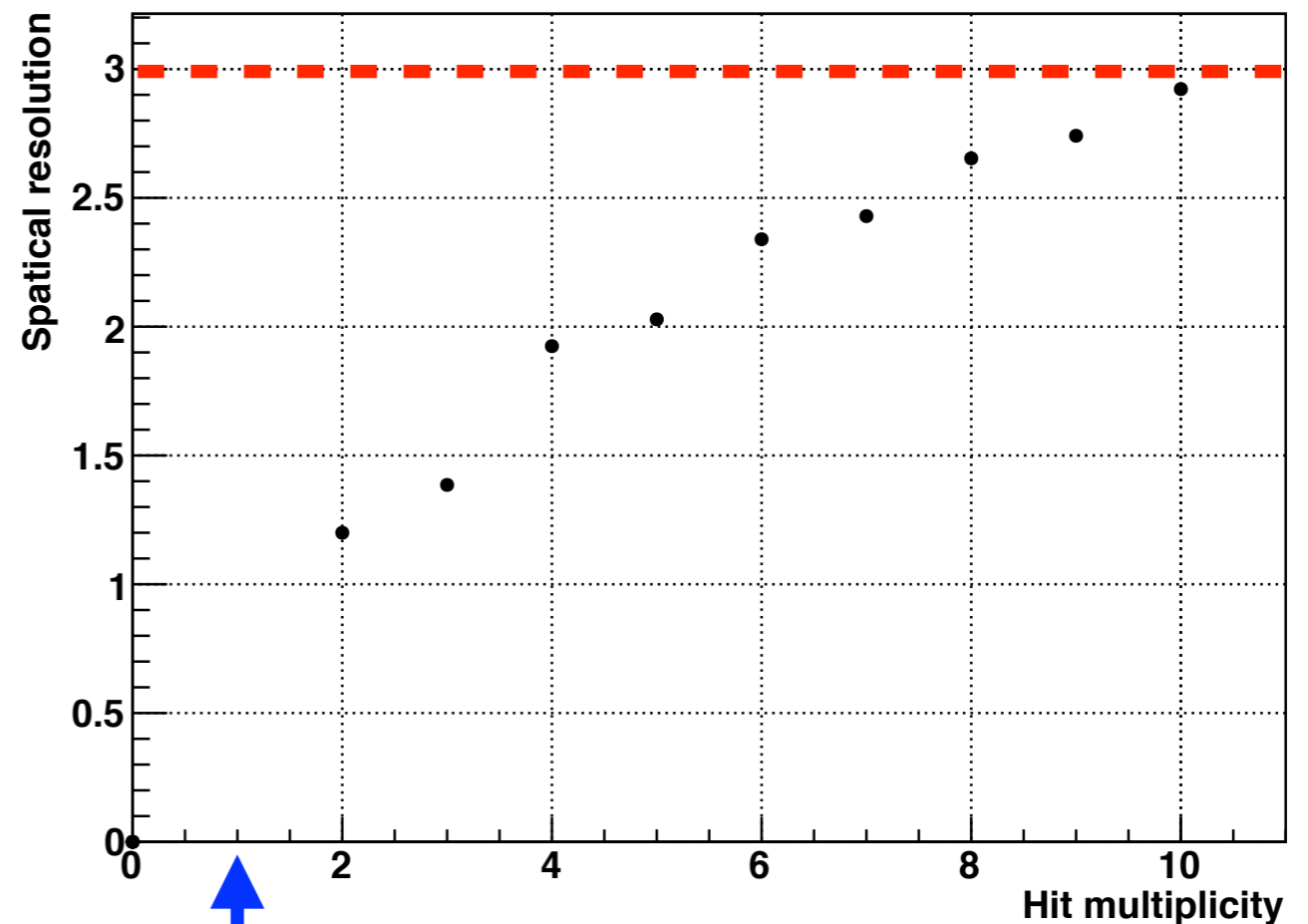
S : Total charge

N : Noise in 1 pixel

M : Hit multiplicity of pixels

- In case of 2 hits : $\delta x = N * a / S$
- **S/N = 17** is assuming.

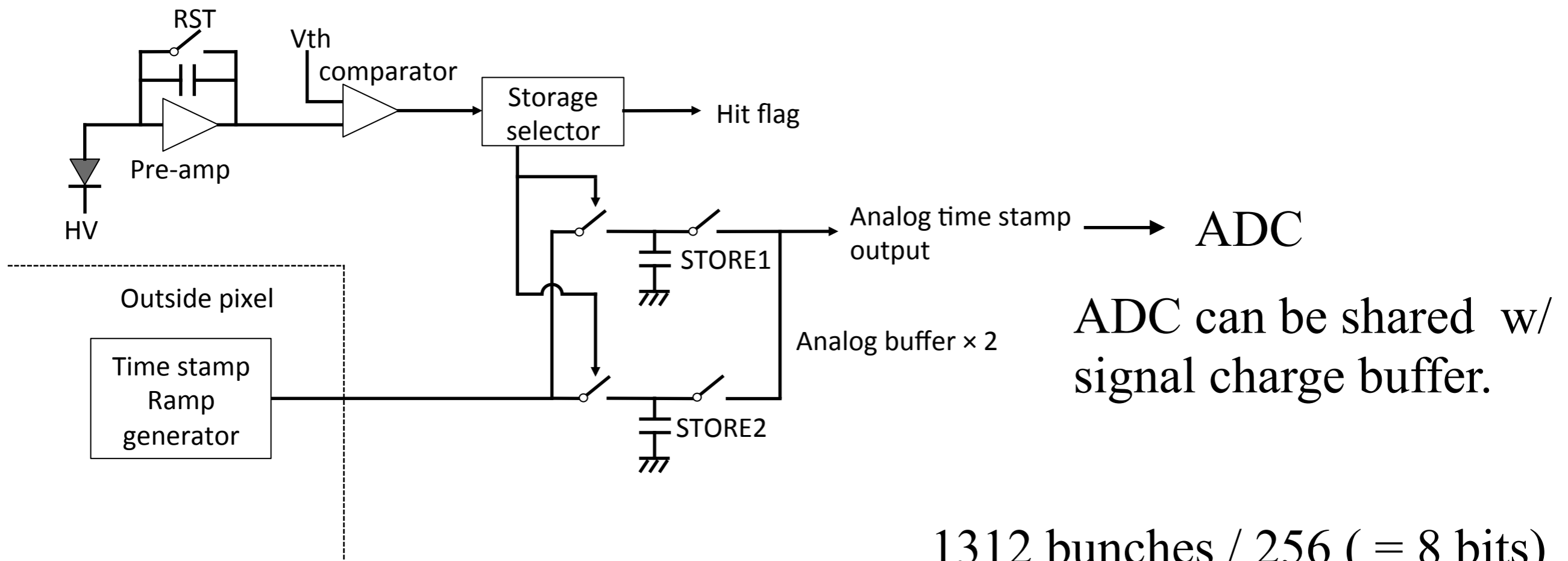
Spatial resolution vs. Hit multiplicity



Resolution = $20/\text{sqrt}(12) \sim 5.8 \mu\text{m}$ in
case of $M = 1 \dots$

Timestamp

- 2 ways
 - Keep digitize information on pixel circuit.
 - Keep charge from ramp generator.



1312 bunches / 256 (= 8 bits)
bunch resolution in principle.

Summary of design

Description	Spec.	Unit	Comment
Pixel size	20 x 20	μ	
Active area size	62.5(H) x 10 (V)	mm	
N of pixels	3125(H) x 500(V)	-	
Thickness	50	μm	1 MIP \sim 3700 e
Noise level	< 200	e	S/N < 17
Readout	ADC 8 bits	-	
Timestamp for bunch	8 bits		Using analog buffer

* Zero-suppression is definitely needed.

** Readout speed and Power consumption need to be considered.

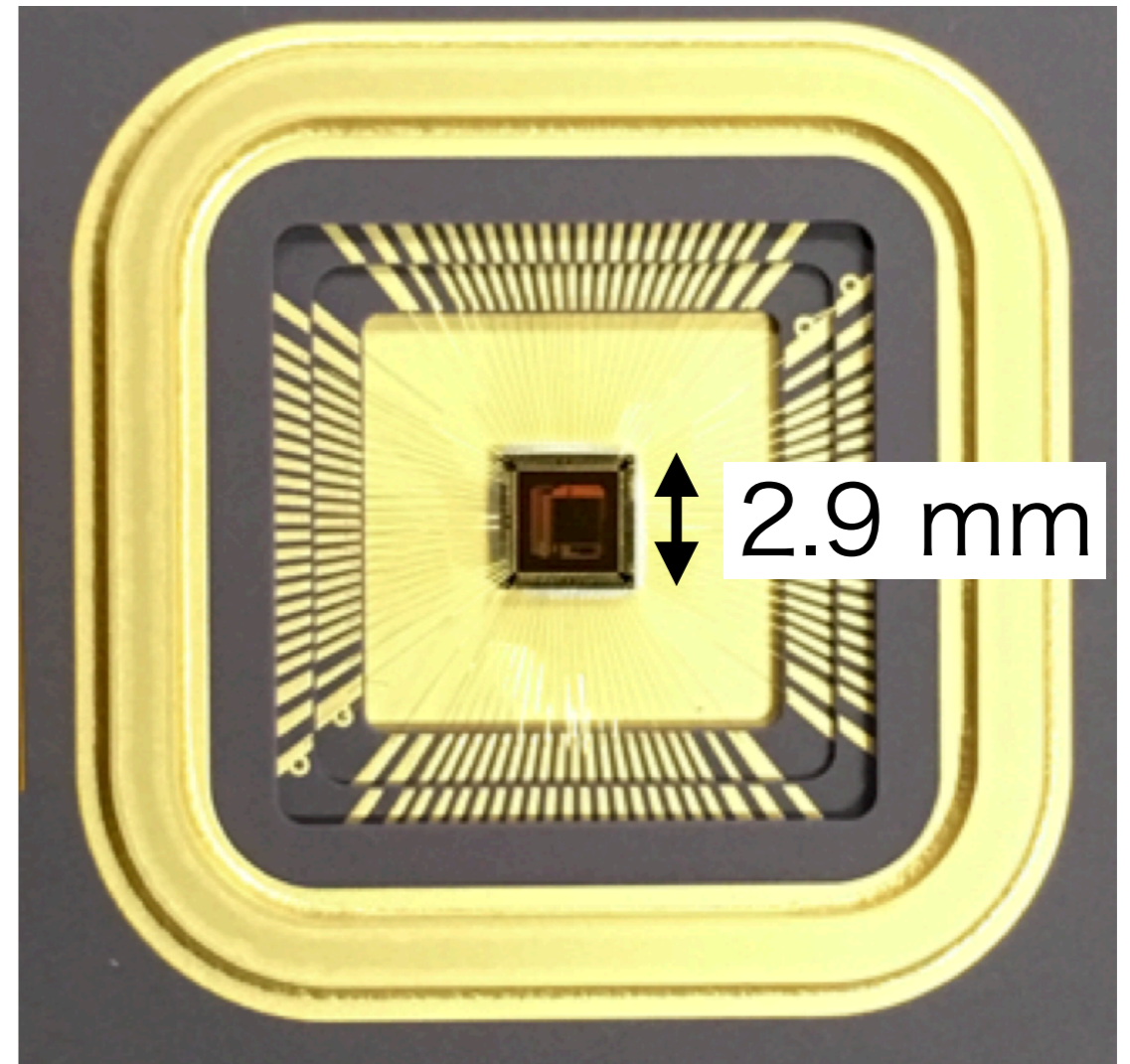
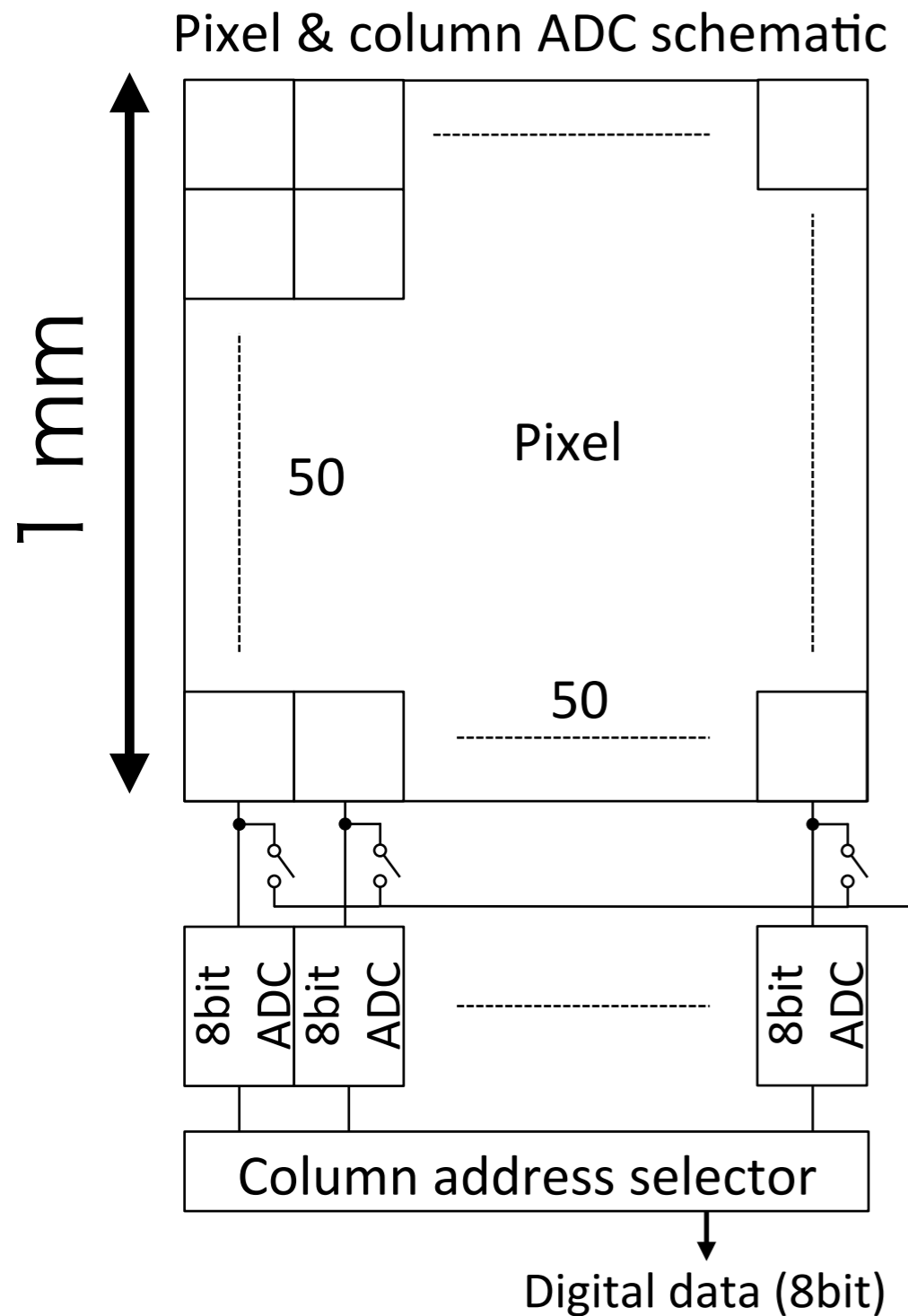
Development plan

- v. 1 : Test for analog circuit
 - Pre-amp
 - x2 analog buffers

Production was done.
Now evaluating performance.
- v. 2 : Test for digital circuit
 - Time stamp circuit (x2 analog buffers)
 - Zero-suppression

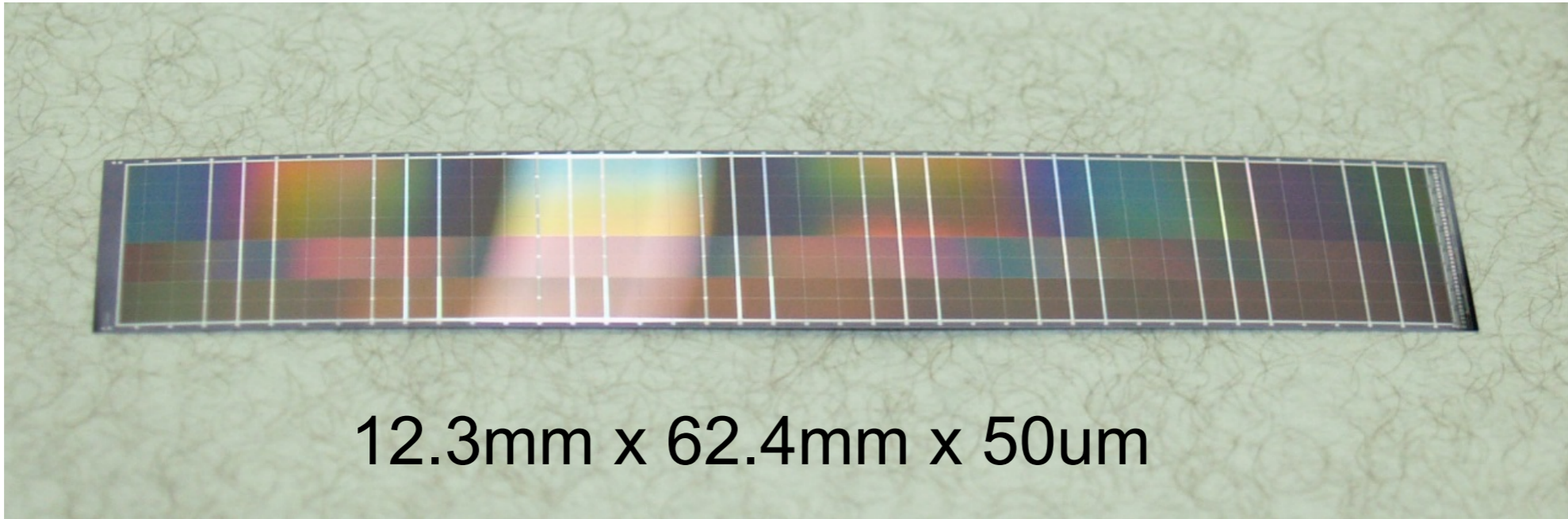
Design was done.
Submitted to production.
- v. 3 : Implementation both analog and digital circuits
- * Grown sensor size needs to be considered.
- ** Pixel size is too small to have buffers...

SOFIST v.1



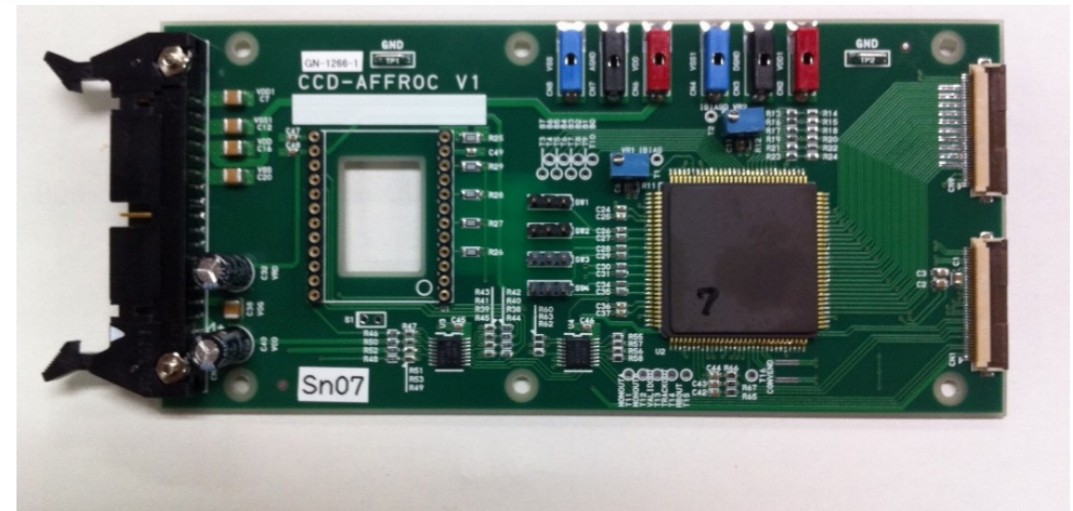
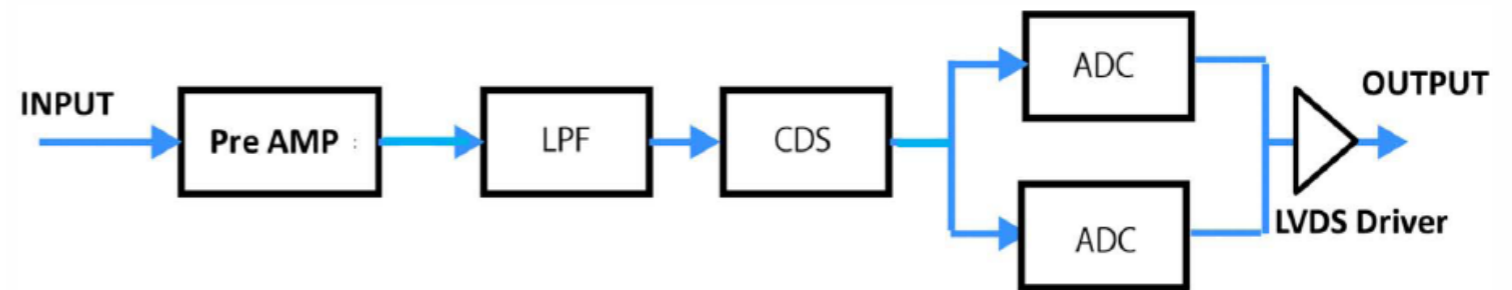
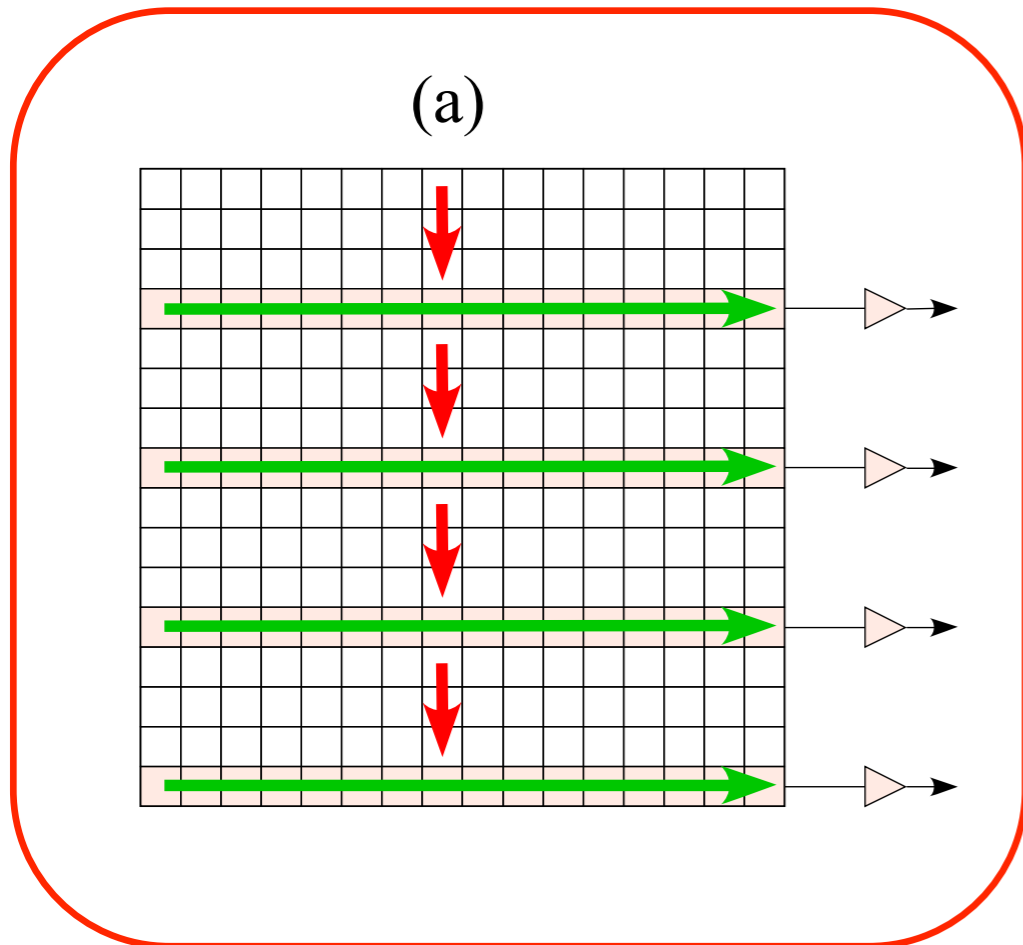
Details in S. Ono and M. Yamada talks in tomorrow

FPCCD (Fine Pixel CCD)



- Pixel size : $5 \times 5 \mu\text{m}^2$
- Active area : $\sim 15 \mu\text{m}$ thick epitaxial layer.
- Wafer thickness : $50 \mu\text{m}$
- Total # of pixels : 10^{10} : needs 10 Mpix/s readout

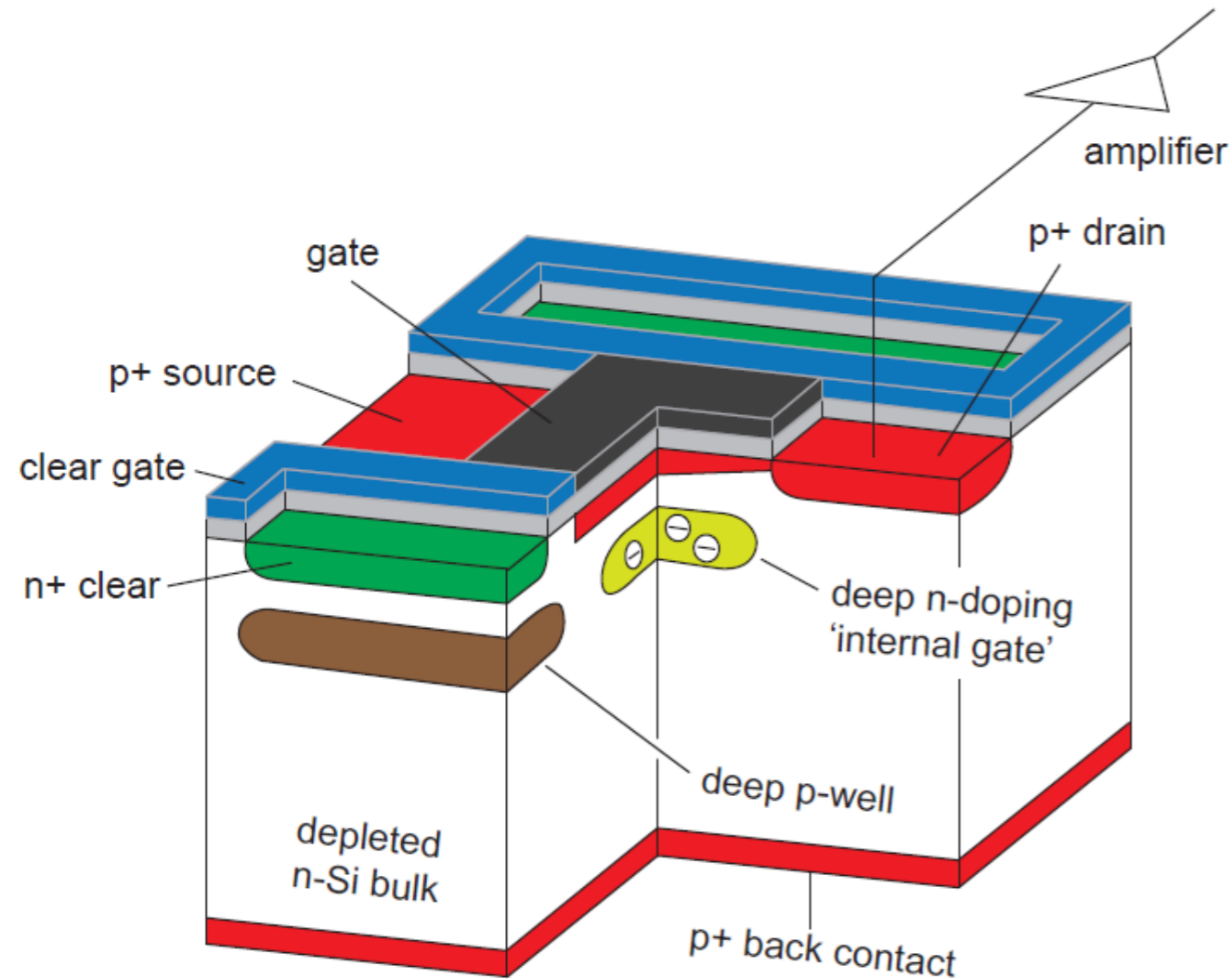
FPCCD readout



- Amplifier and ADC need to be prepared.
- Readout : 10 Mpix/s (currently achieved 2.5 Mpix/s)

DEPFET

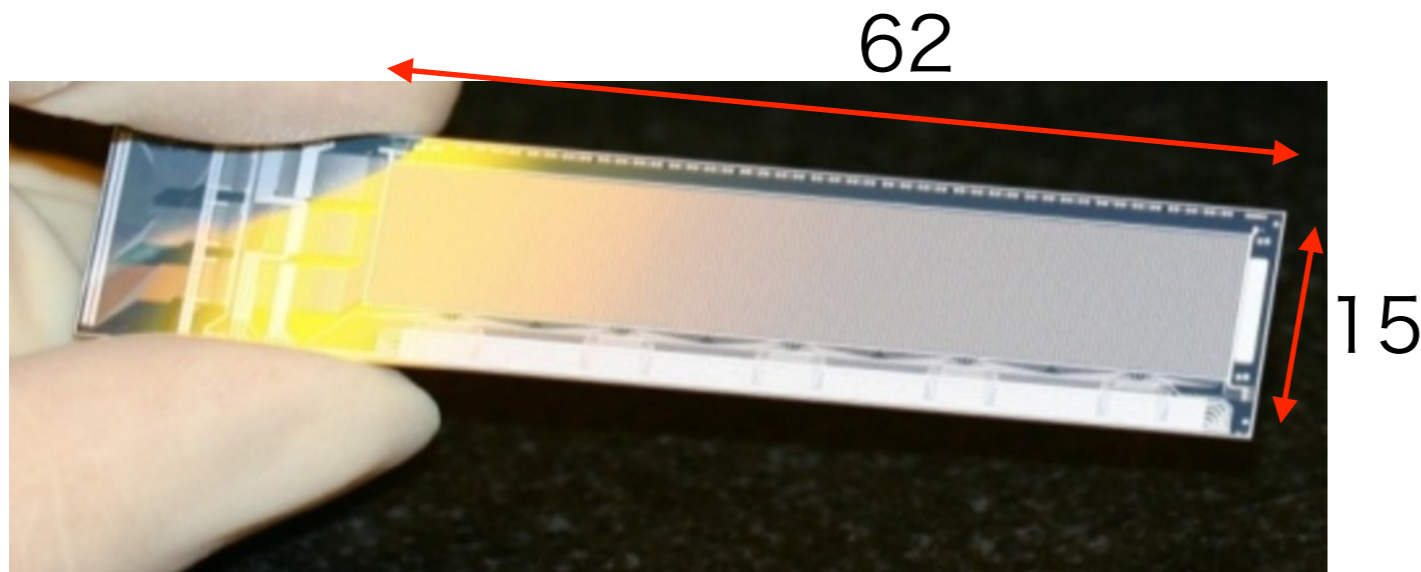
(DEpleted P-channel FET)



- Pixel size : $20 \times 20 \mu\text{m}^2$
- Fully depleted : $\sim 50 \mu\text{m}$.
- The charge stored in the internal gate.

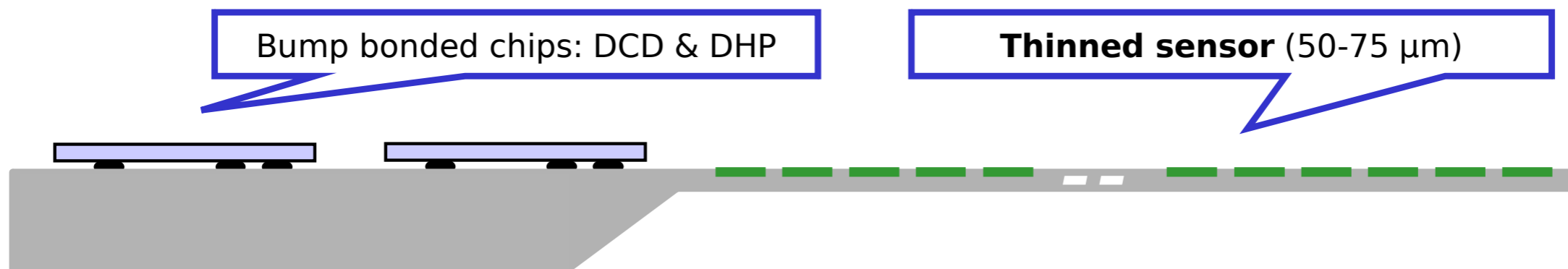
- Will be installed at the Bell2 experiment

DEPFET spec.



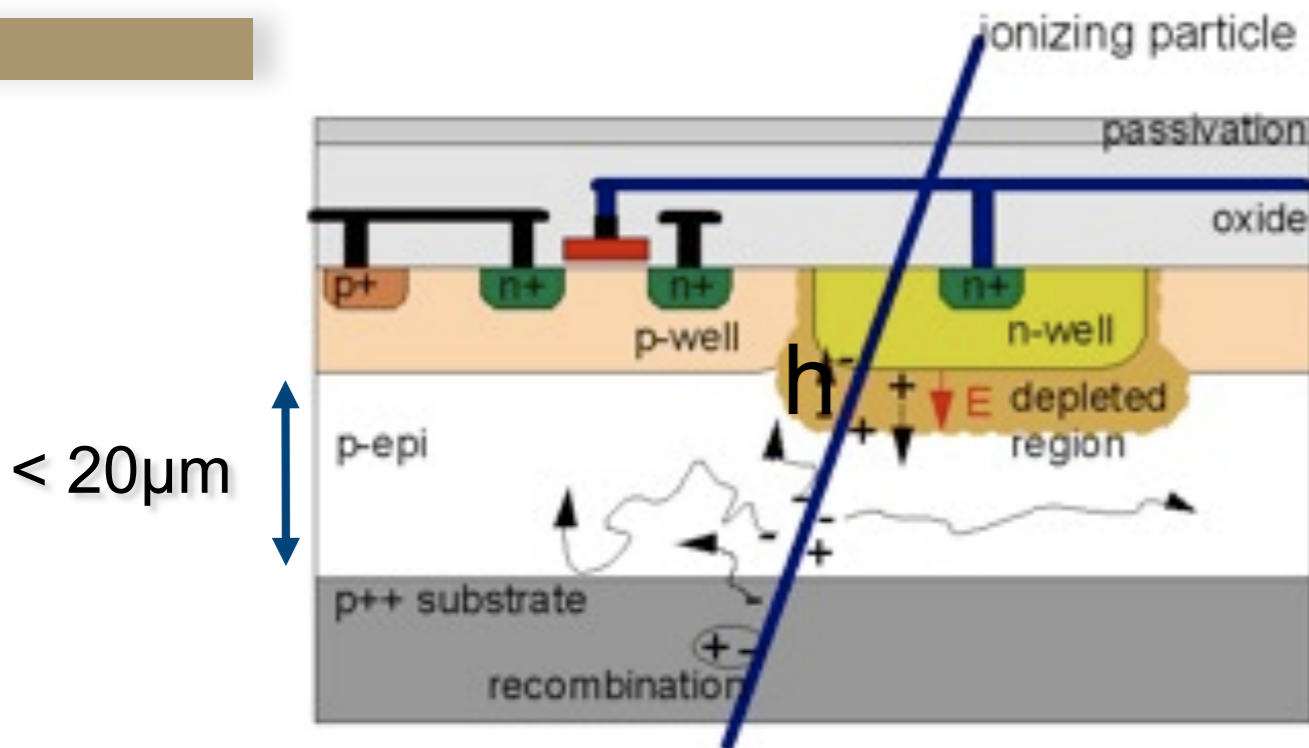
- Spatial resolution :
 - 2.3 - 3.5 μm
- Material budget :
 - 0.15 X_0 (including support frame)
- Frame rate :
 - 40 μs / frame w/ rolling shutter readout.
 - 25 times readout / train
- Micro-channel cooling

2 ASICs for digitizing and control



PLUME

(Pixelated Ladder with Ultra-low Material Embedded)



- Pixel size : $18.4 \times 18.4 \mu\text{m}^2$
- Active area is p-epitaxial layer $< 20 \mu\text{m}$
- ASICS on chip
- Based on MAPS (Monolithic Active Pixel Sensor)

- MAPS was installed and is operating at RHIC STAR experiment (2014)

- https://www.google.co.jp/url?sa=t&rct=j&q=&esrc=s&source=web&cd=6&ved=0CEIQFjAF&url=https%3A%2F%2Findicofic.uv.es%2Findicofic%2FmaterialDisplay.py%3FcontribId%3D666%26sessionId%3D29%26materialId%3Dslides%26confId%3D2025&ei=iOjiU7fRNzl8AXm7oH4Dw&usg=AFQjCNENTD1w2gpNY5N9-zTP1QSo-LyYiA&sig2=XGv_eUsBycWJM-D-PgXHTA&bvm=bv.72676100,d.dGc

- Target to ALICE and ILC

Most of all functions are on sensor

MIMOSA26: 1st MAPS WITH INTEGRATED \emptyset

Ingrid-Maria Gregor, Ultra-light double-sided ladders for a LC vertex detector

- Testability: several test points implemented all along readout path
 - Pixels out (analogue)
 - Discriminators
 - Zero suppression
 - Data transmission

- Row sequencer
- Width: $\sim 350 \mu\text{m}$

- 1152 column-level discriminators
 - offset compensated high gain preamplifier followed by latch

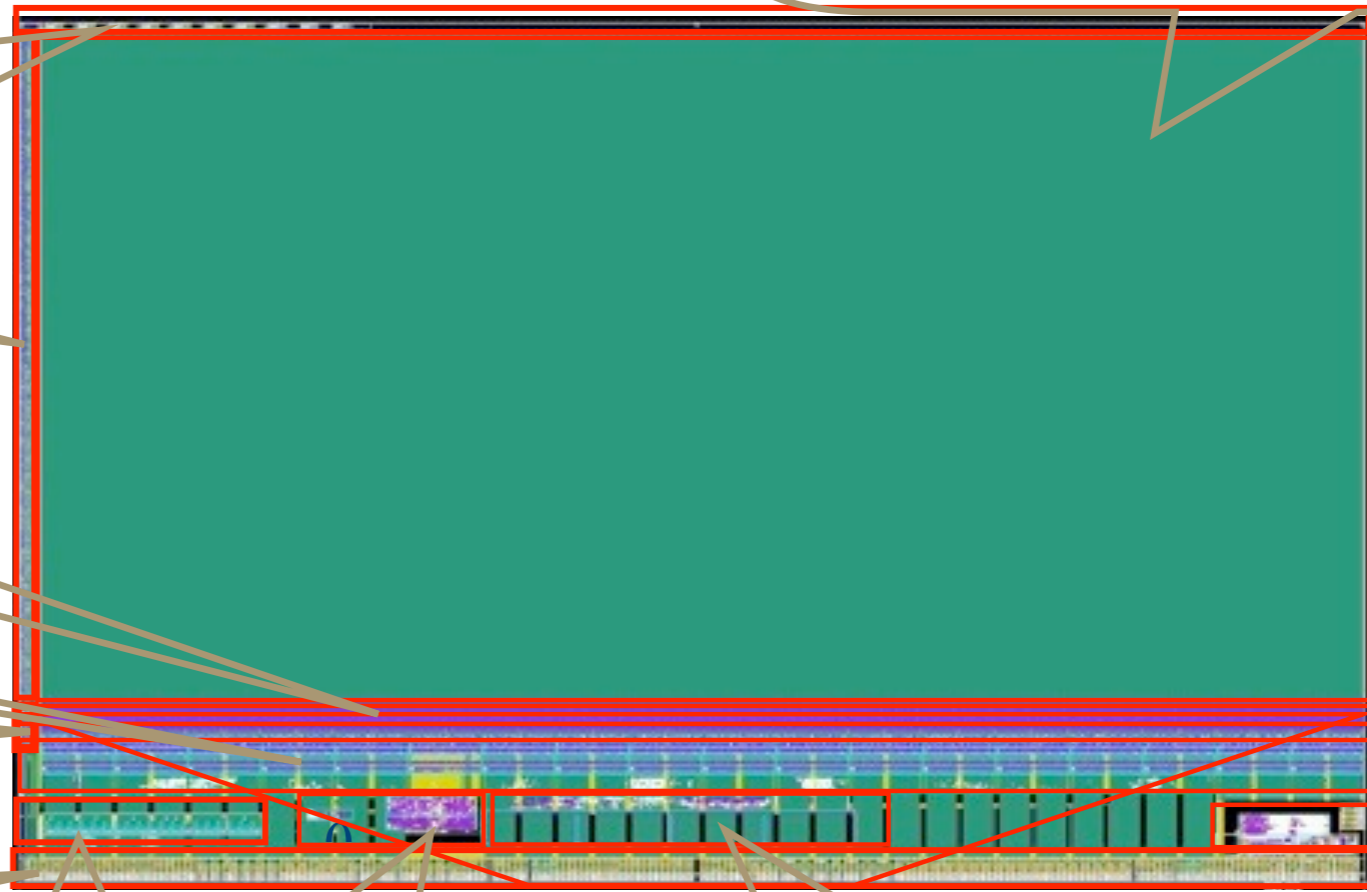
- Zero suppression logic

- Reference Voltages Buffering for 1152 discriminators

- I/O Pads
 - Power supply Pads
 - Circuit control Pads
 - LVDS Tx & Rx

CMOS 0.35 μm OPTO technology
Chip size : 13.7 x 21.5 mm²

- Pixel array: 576 x 1152, pitch: 18.4 μm
- Active area: $\sim 10.6 \times 21.2 \text{ mm}^2$
- In each pixel:
 - Amplification
 - CDS (Correlated Double Sampling)



- Current Ref.
- Bias DACs

- Readout controller
- JTAG controller

- Memory management
- Memory IP blocks

- PLL, 8b/10b optional

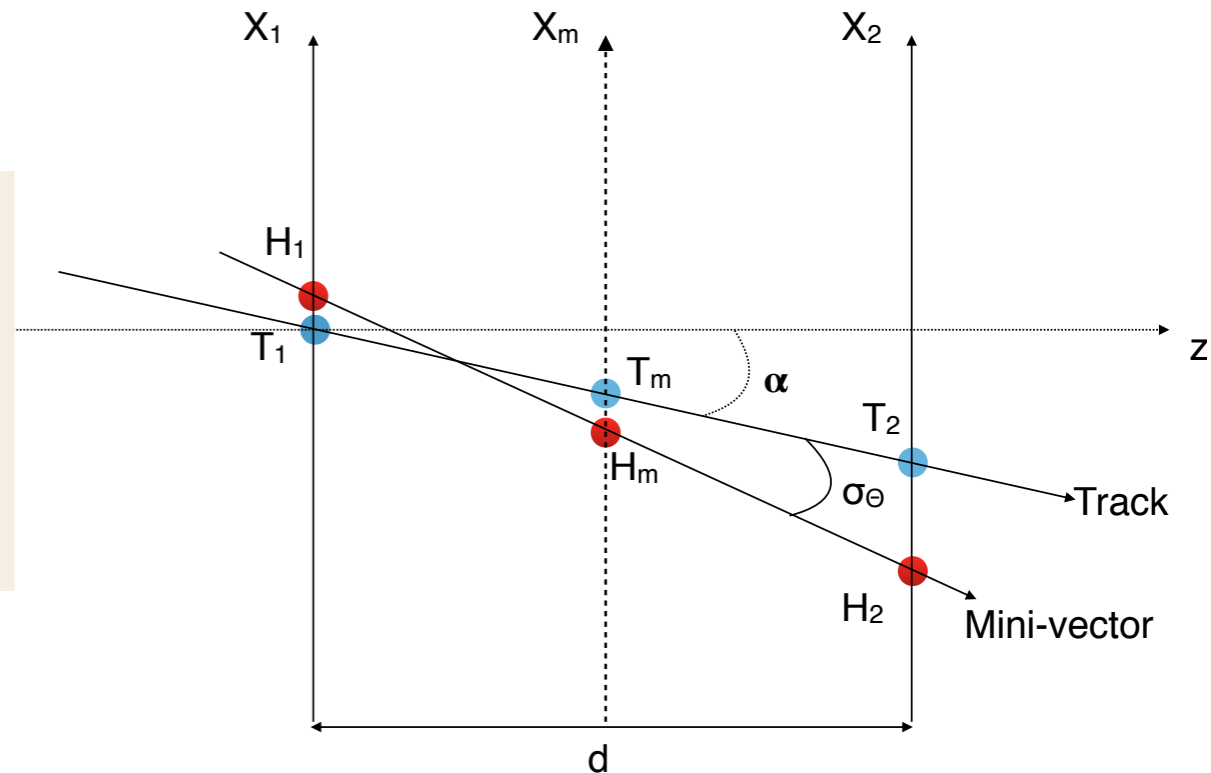
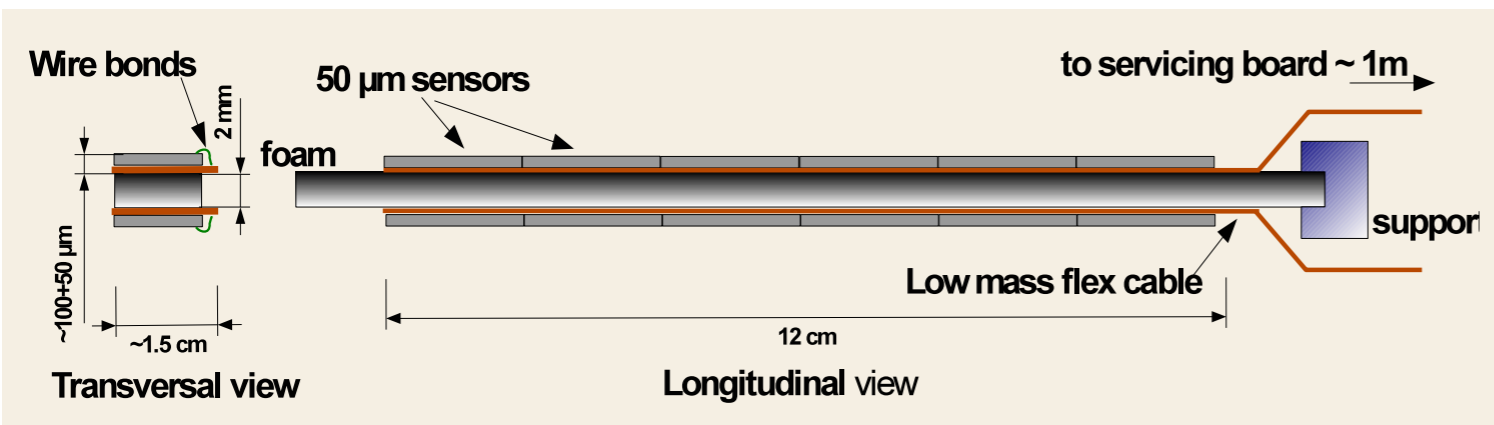
See Ref. C. Hu et al., TWEPP-09



Ingrid-Maria Gregor (PLUME)
LC Forum 2013 at DESY

- Frame rate : 100 μs / frame w/ rolling shutter readout.

Double sensor in 1 layer



- Special resolution is achieved $\sim 3.5 \mu\text{m}$ using 2 sensors even if binary readout.

Summary

	SOFIST	FPCCD	DEPFET	PLUME
Pixel size (position resolution (μm))	20 x 20 (<3)	5 x 5 <1.4	20 x 20 2.3-3.5	18.4 x 18.4 3.5
Thickness (μm) [Active area]	50 [Full]	50 [~15]	50 [Full]	50 [~20]
Material budget (%X (Not final value))	0.05 + **	0.25	0.15	0.35
ASIC on chip	Yes	No	No	Yes
Row read rate [Goal]	2.5 MHz [10 MHz]	2.5 MHz [10 MHz]	10 MHz [40 MHz]	?
Frame rate [μs]	Readout btw train w/ timestamp	Readout btw train	40 μs (25 / train)	~100 μs (10 / train)
Frame rate [μs]	ADC on chip	ADC	ADC	Binary

Advantages of SOFIST (SOI)

- Full depleted on 50 μm thickness
 - vs. PLUME (15 μm)
- Most of functions are on chip
 - vs. DEPFET
- Best bunch identification w/ on-chip buffers
 - SOFIST : 1312/256 (using 256 bits ADC readout)
 - DEPFET : 1312/25, PLUME : 1312/10

Backup

Consideration

- Pay load is almost full at v.2
 - Actually full w/ $25\mu\text{m}^2$ pixel.
- More buffers may need for the low occupancy operation.

Occupancy study by Mori-san for FPCCD

表 5.1: 各レイヤーの占有率 (250 GeV)

レイヤー	占有率 (%)	直接ペアの占有率 (%)	反跳ペアの占有率 (%)
	6.7	6.1	0.6
0	0.561	0.506	0.055
1	0.353	0.319	0.034
2	0.056	0.053	0.003
3	0.045	0.043	0.002
4	0.010	0.010	0.001
5	0.009	0.008	0.001

表 5.3: 各レイヤーの占有率 (500 GeV)

レイヤー	占有率 (%)	直接ペアの占有率 (%)	反跳ペアの占有率 (%)
	14.9	12.6	2.3
0	1.244	1.053	0.191
1	0.779	0.661	0.118
2	0.122	0.113	0.009
3	0.100	0.092	0.008
4	0.023	0.021	0.002
5	0.020	0.018	0.002

表 5.2: 各レイヤーの占有率 (350 GeV)

レイヤー	占有率 (%)	直接ペアの占有率 (%)	反跳ペアの占有率 (%)
	8.4	7.5	0.9
0	0.702	0.622	0.080
1	0.443	0.392	0.052
2	0.067	0.063	0.004
3	0.055	0.052	0.004
4	0.013	0.012	0.001
5	0.011	0.010	0.001

表 5.4: 各レイヤーの占有率 (1 TeV)

レイヤー	占有率 (%)	直接ペアの占有率 (%)	反跳ペアの占有率 (%)
	100	40.5	100
0	12.752	3.386	9.367
1	7.010	2.099	4.911
2	0.458	0.345	0.113
3	0.379	0.281	0.098
4	0.099	0.065	0.034
5	0.089	0.057	0.032

Ratio of cross size of pixel : x16

Ratio of multiple hits : x0.75 -> FPCCD x12 is occupancy of SOFIST.

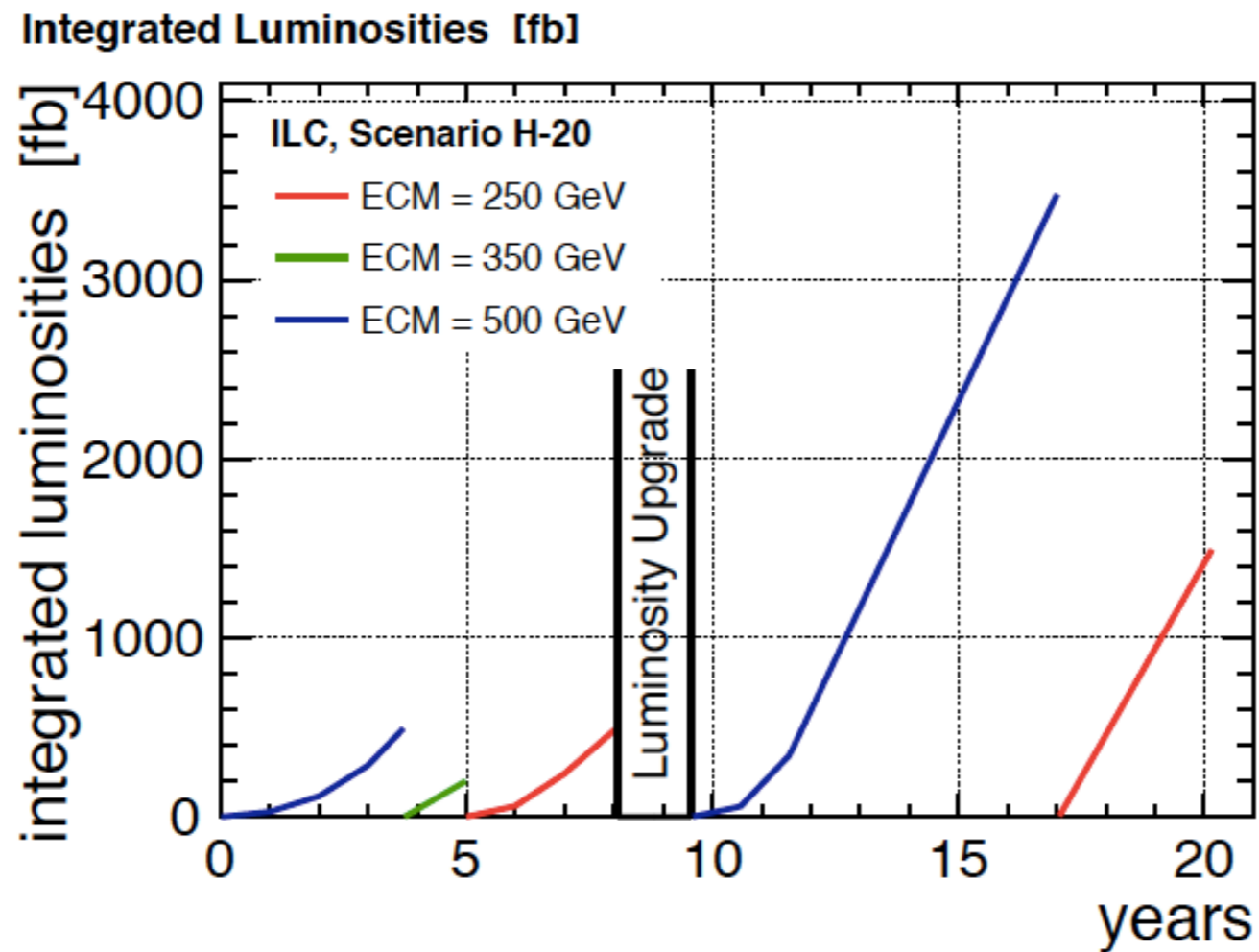
2 bunches -> $0.149^2 \sim 0.02$

Consideration

- Pay load is almost full at v.2
 - Actually full w/ $25\mu\text{m}^2$ pixel.
- More buffers may need for the low occupancy operation.
- Needs more circuit spacing...
 - 3D technology (CMOS layers)
 - Technology has been developing by SOI group.

Standard Sample ILC Running Scenario

- Adopted by the LCB (Linear Collider Board)
- ILC 500 GeV (1 TeV is optional and not included here)



Total

250GeV	1500fb-1
350GeV	200fb-1
500GeV	4000fb-1

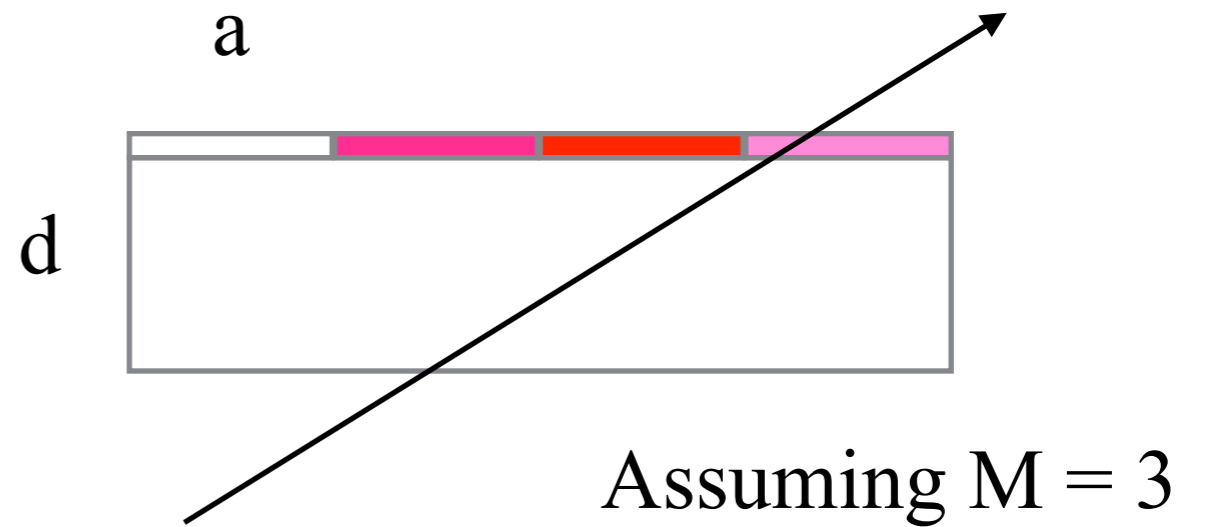
Luminosity upgrade :
5 Hz -> 10 Hz

Accelerator talk by K. Yokoya

2

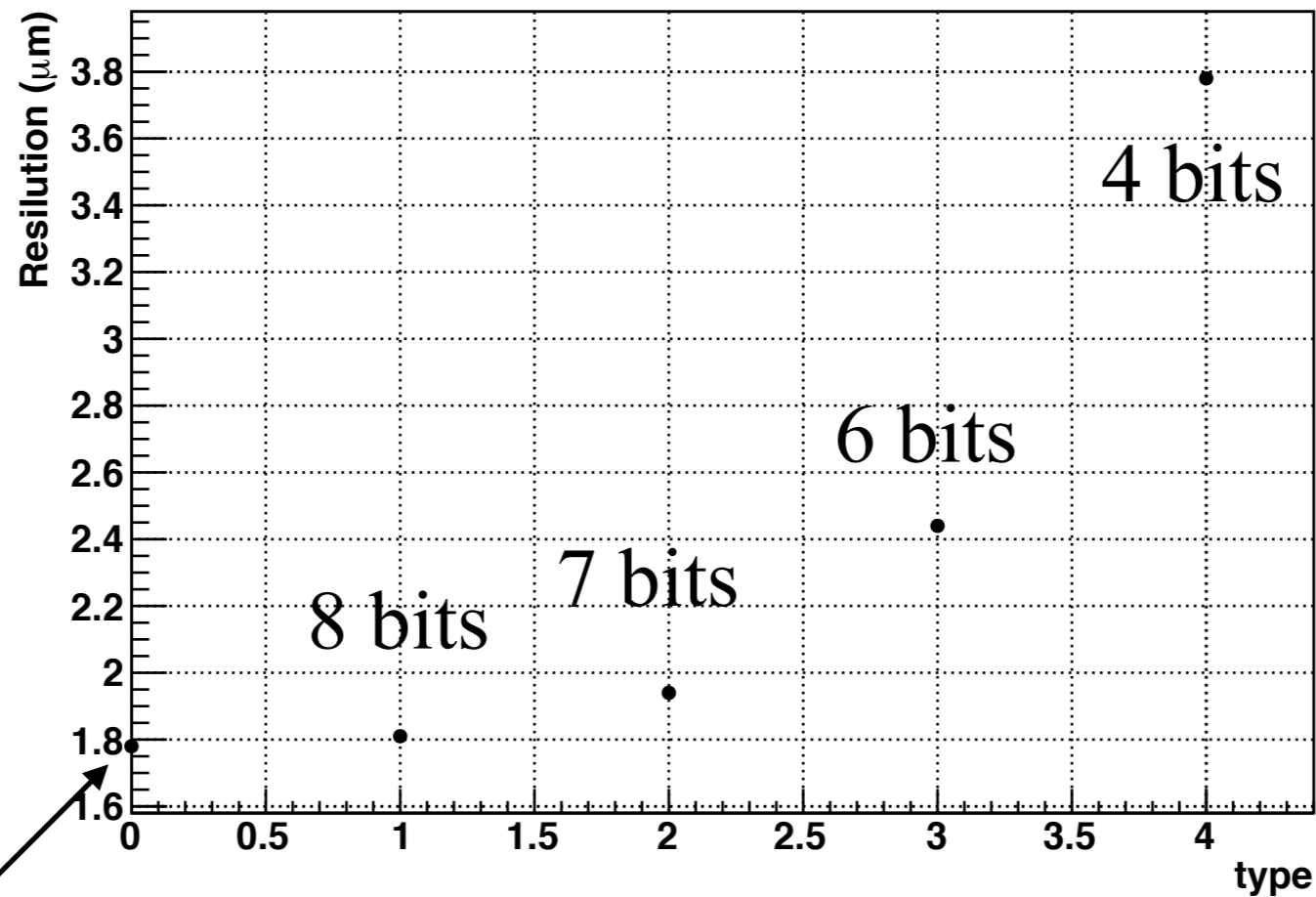
ADC requirement

Range requirement : 5 MIP



Assuming $M = 3$

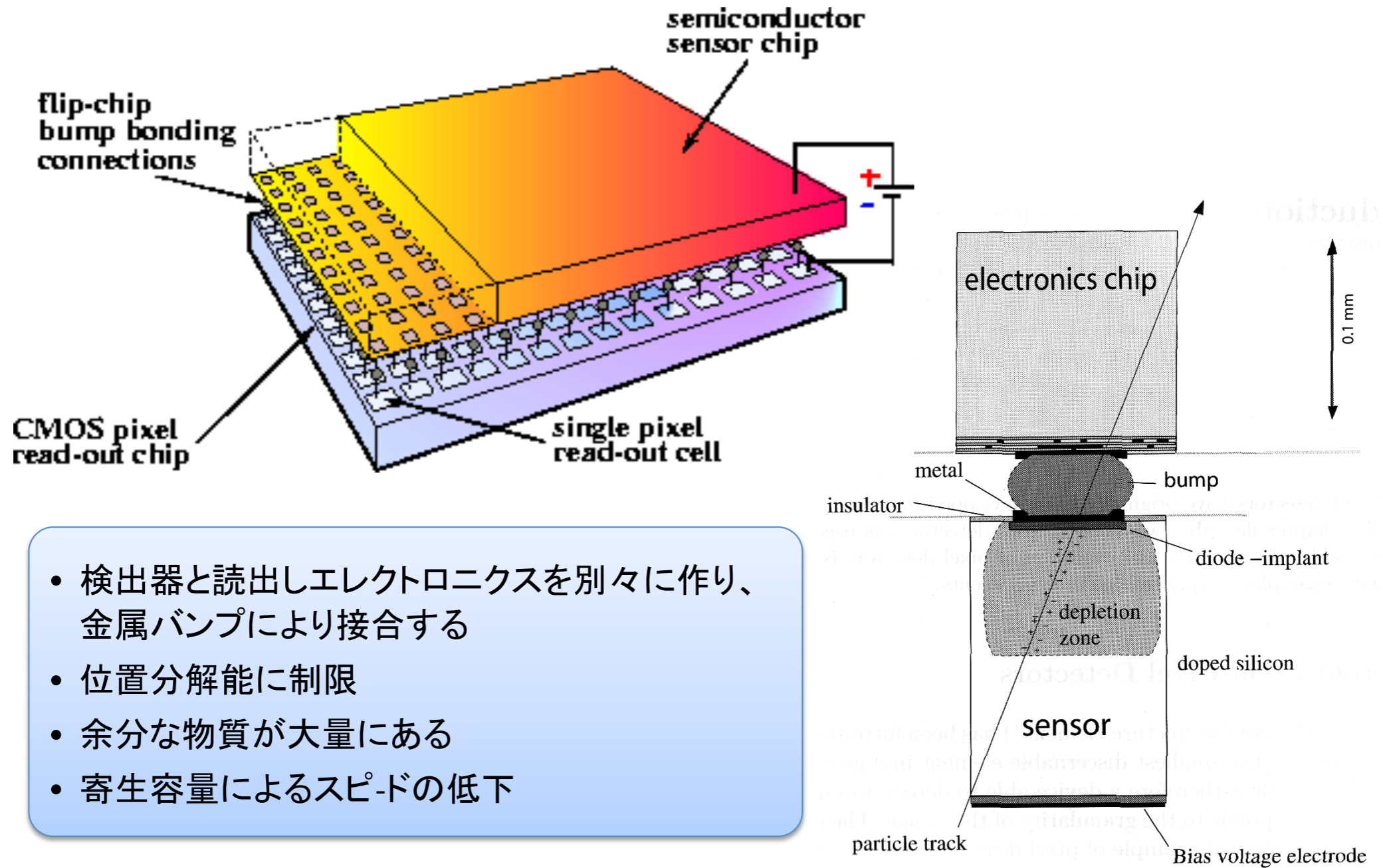
Resolution w/ ADC effect



No ADC conversion

8 bits looks suitable

ピクセル検出器の現状



- 検出器と読出しエレクトロニクスを別々に作り、金属バンプにより接合する
- 位置分解能に制限
- 余分な物質が大量にある
- 寄生容量によるスピードの低下

Hit multiplicity of FPCCD

Mori-san's master thesis

http://epx.phys.tohoku.ac.jp/eeweb/paper/2014_Mthesis_mori.pdf

(1) クラスタ内のピクセル数

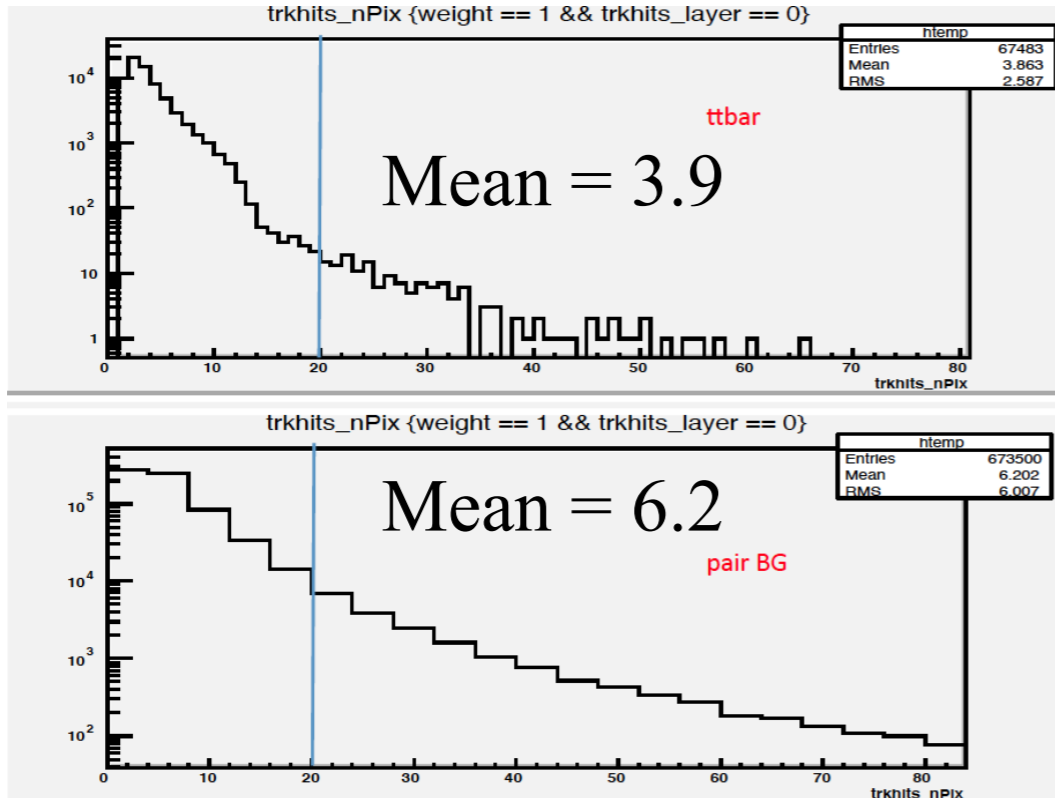


図 5.2: クラスタ内のピクセル数分布

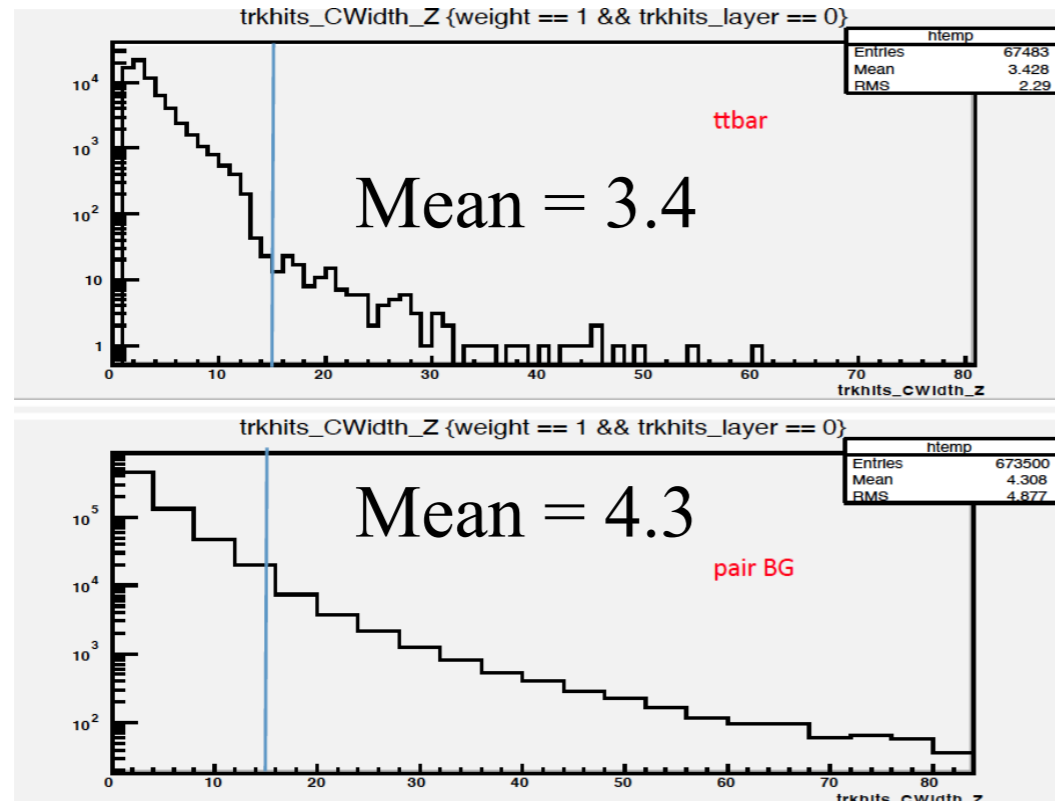


図 5.4: クラスタの ζ 方向の長さ分布

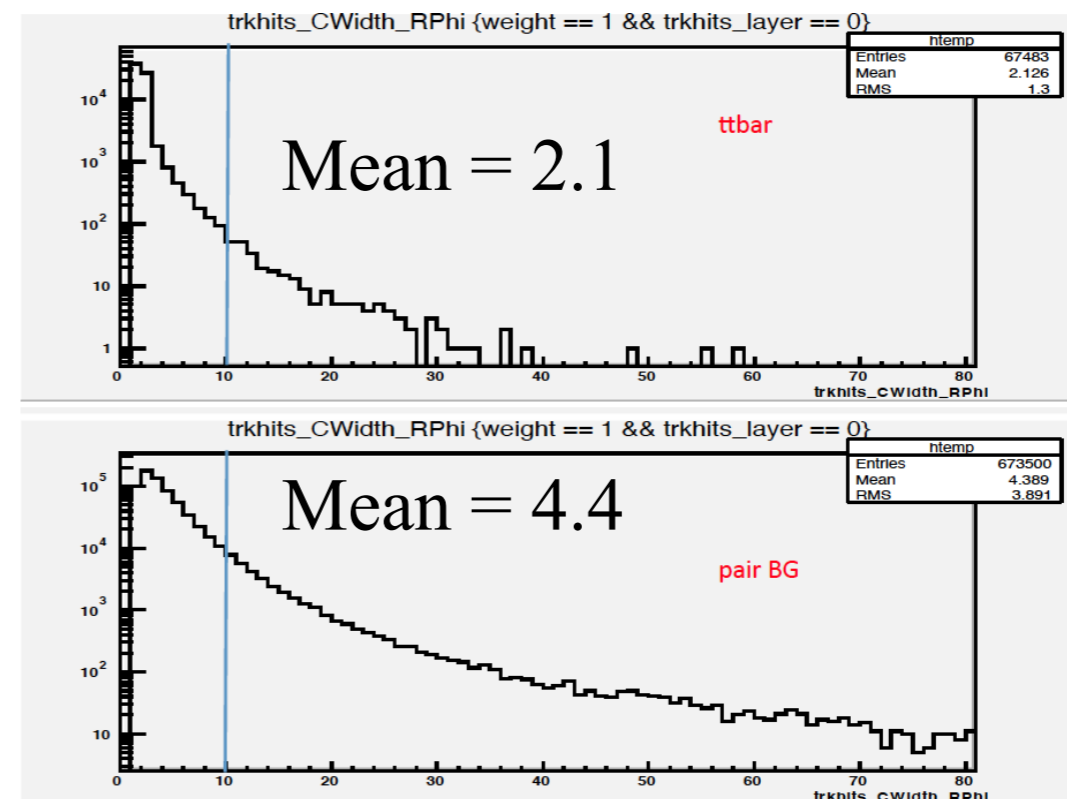
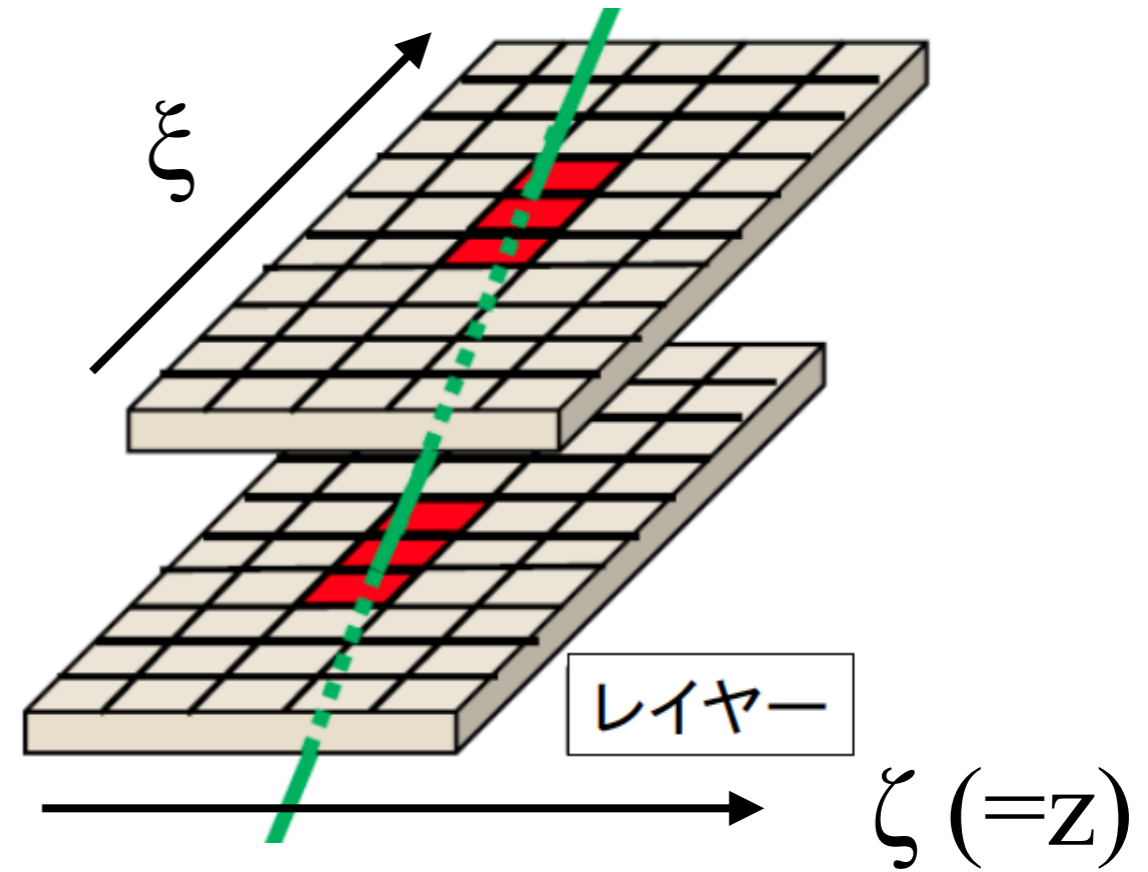


図 5.3: クラスタの ξ 方向の長さ分布

For SOI detector

- FPCCD : 5 um pitch, 15 um full depletion
- SOI : 20 um pitch, 50 um full depletion
- -> Multiplicity will be times $(5/20)*(50/15) = 0.75$
- The multiplicity in case of $tt \rightarrow 6\text{jets}$ looks up to $M=10$.

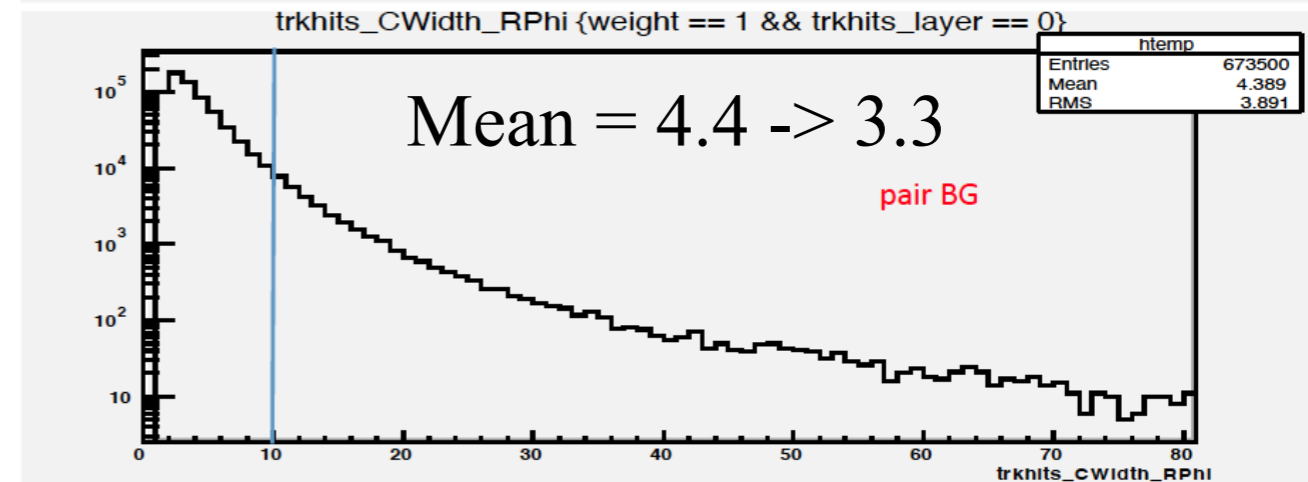
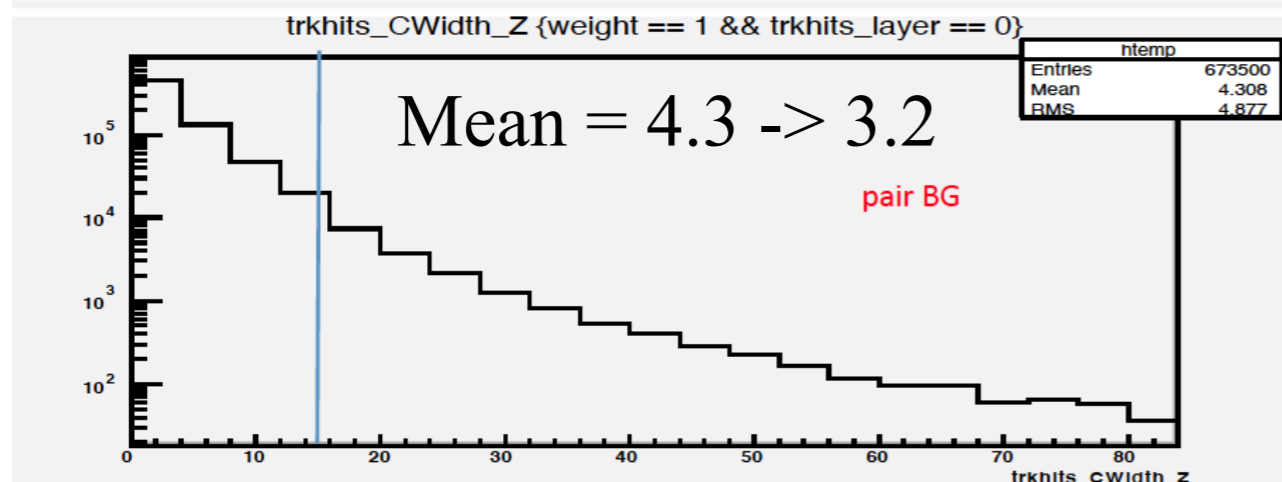
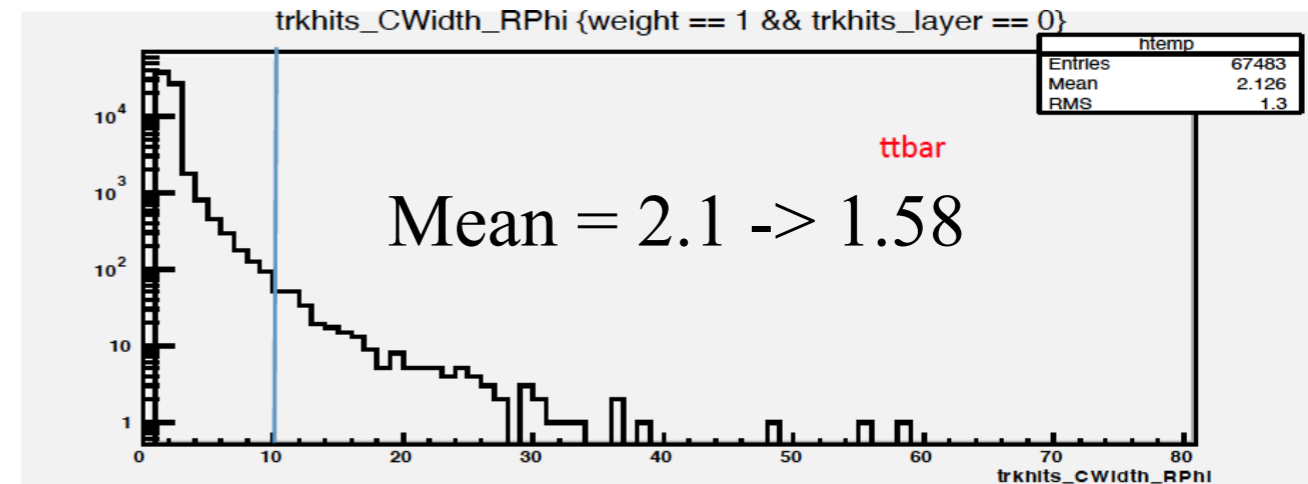
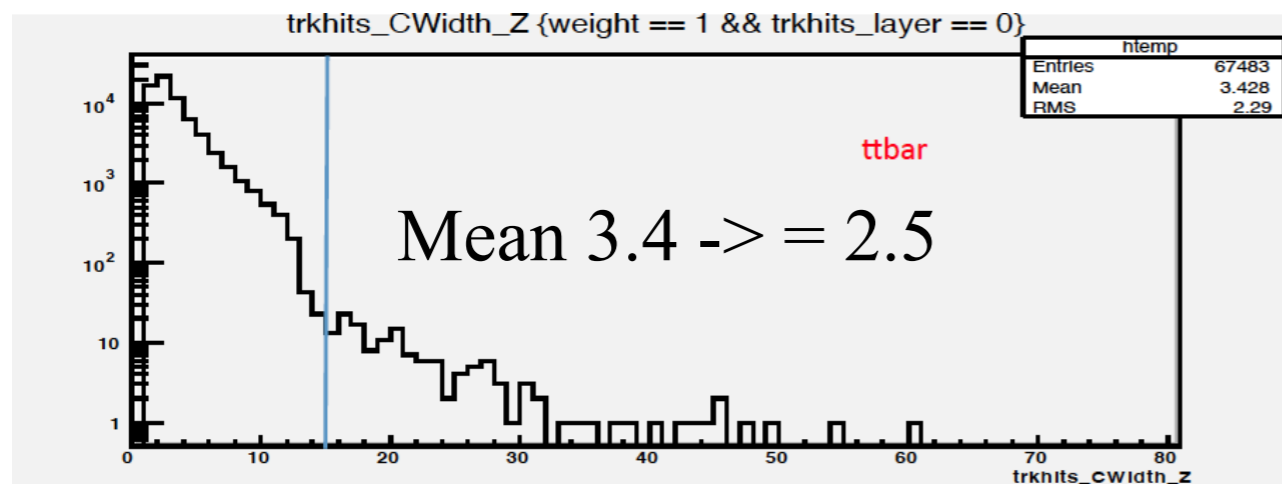
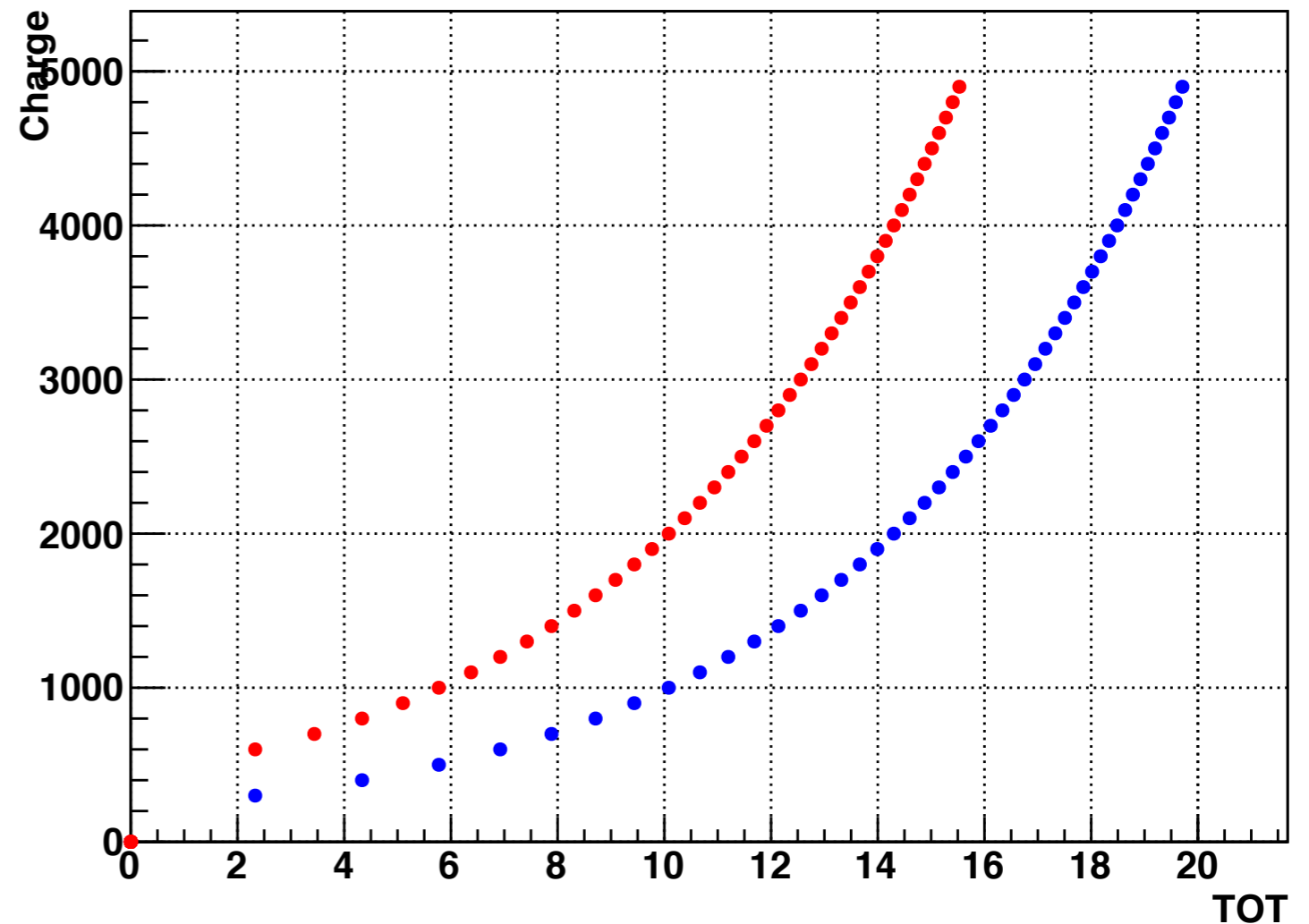
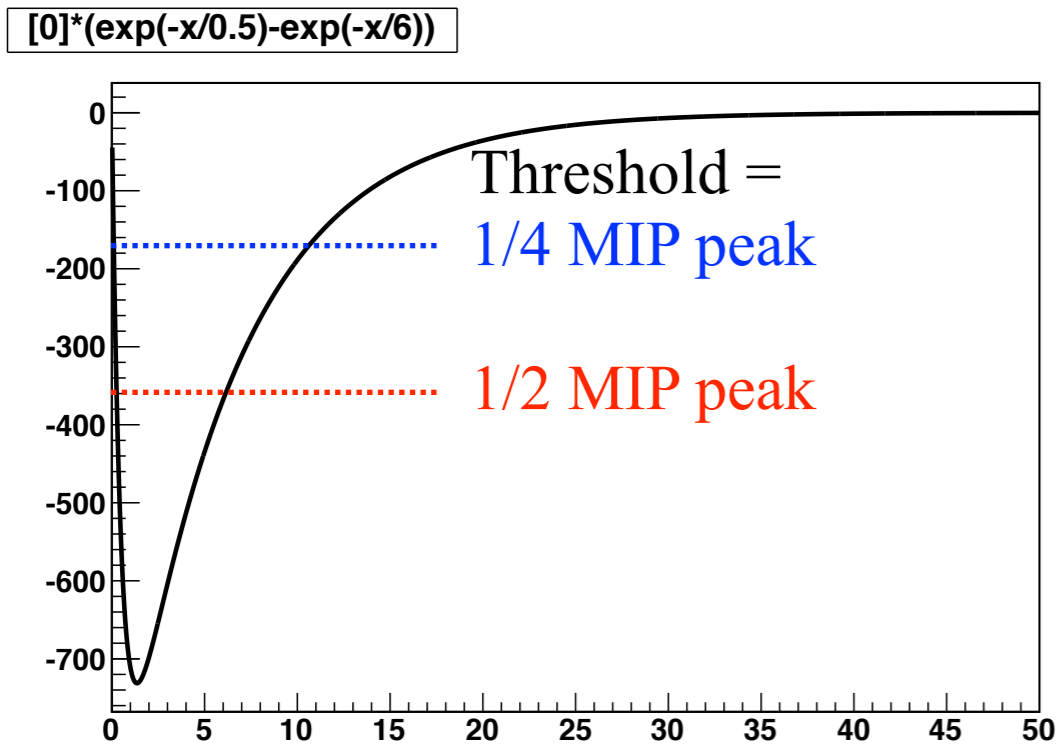


図 5.4: クラスターの ζ 方向の長さ分布

図 5.3: クラスターの ξ 方向の長さ分布

Ideal case for TOT

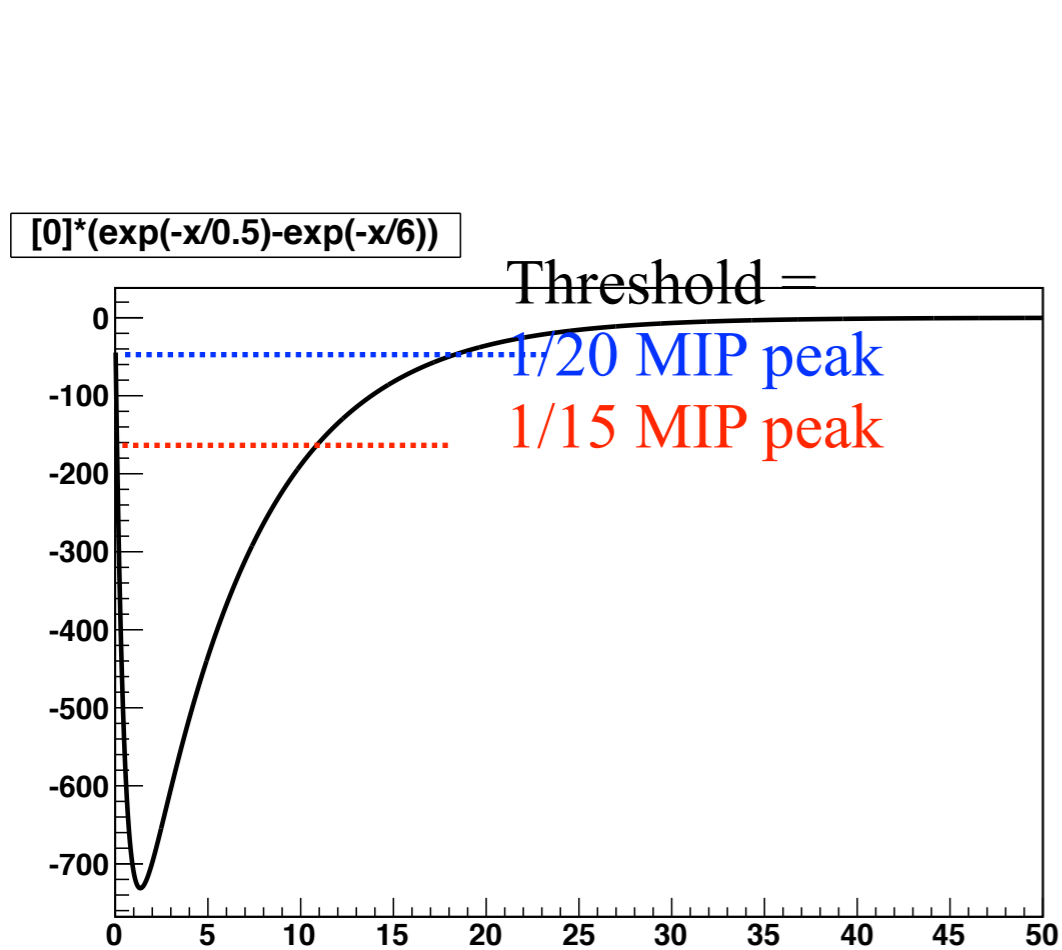
Charge vs. TOT



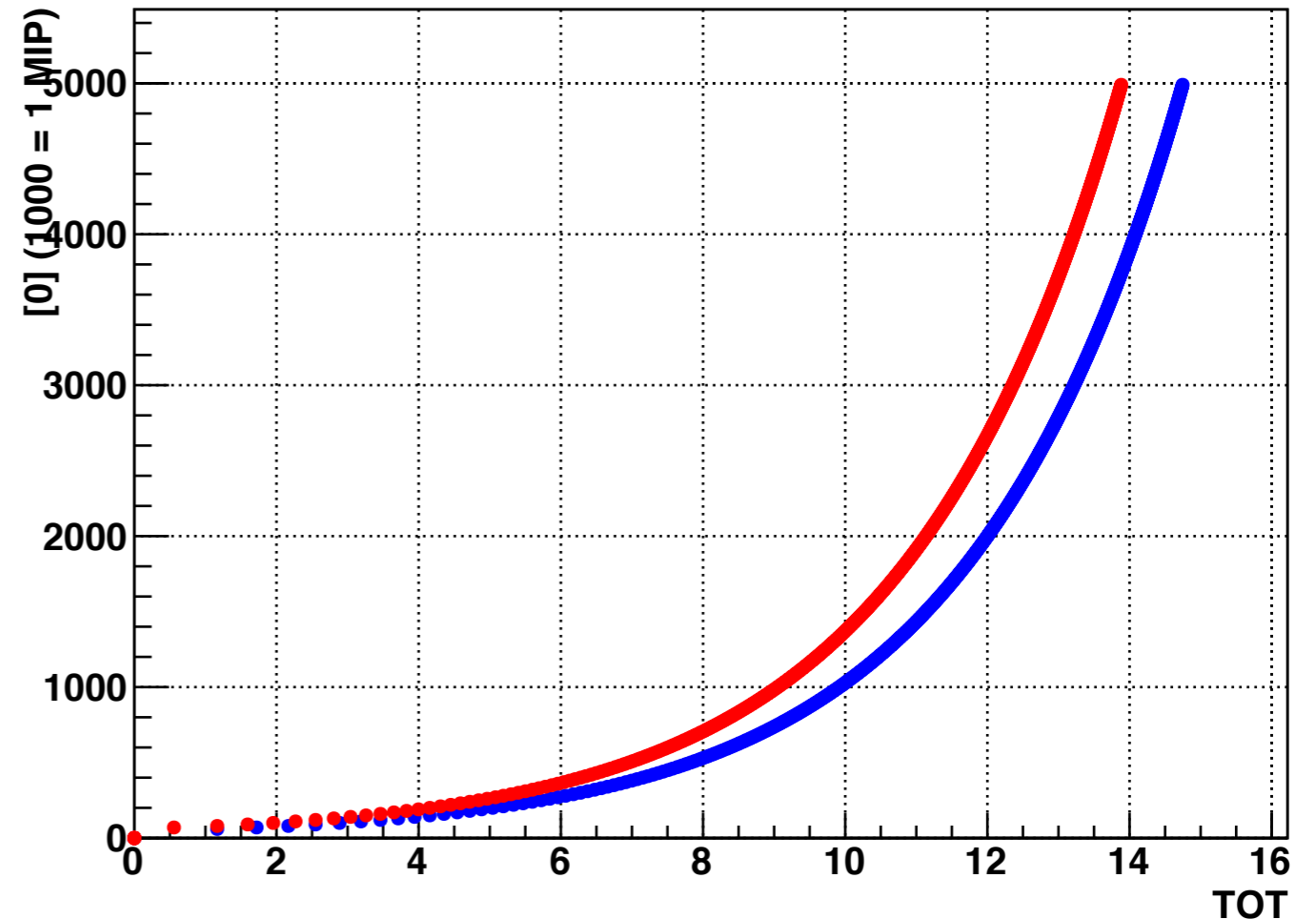
- 低いエネルギー側でnon-linearity
- 低いエネルギーをカバーする為にはThreshold低めが必要
- エネルギー情報は必要なので普通のADCの方が良い

低いエネルギー側で分解能が良い

低いエネルギーを見る為に低いthreshold



Charge vs. TOT

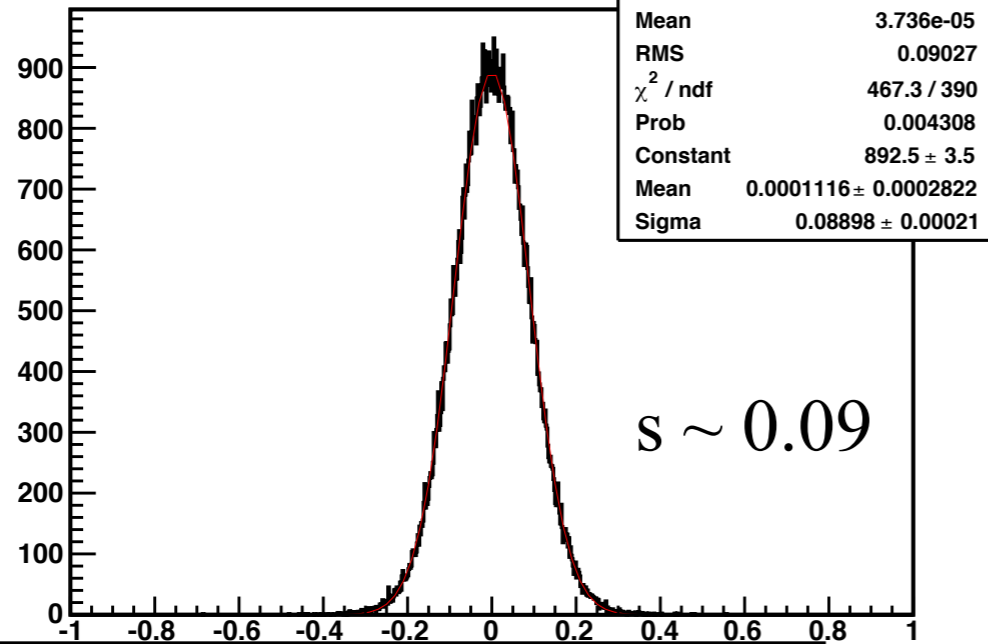


- 1/20 MIPをpol7 fitして関数化して、位置分解能に対する影響を見る。
- 横軸は4 bits (=16) に収まる様に調整

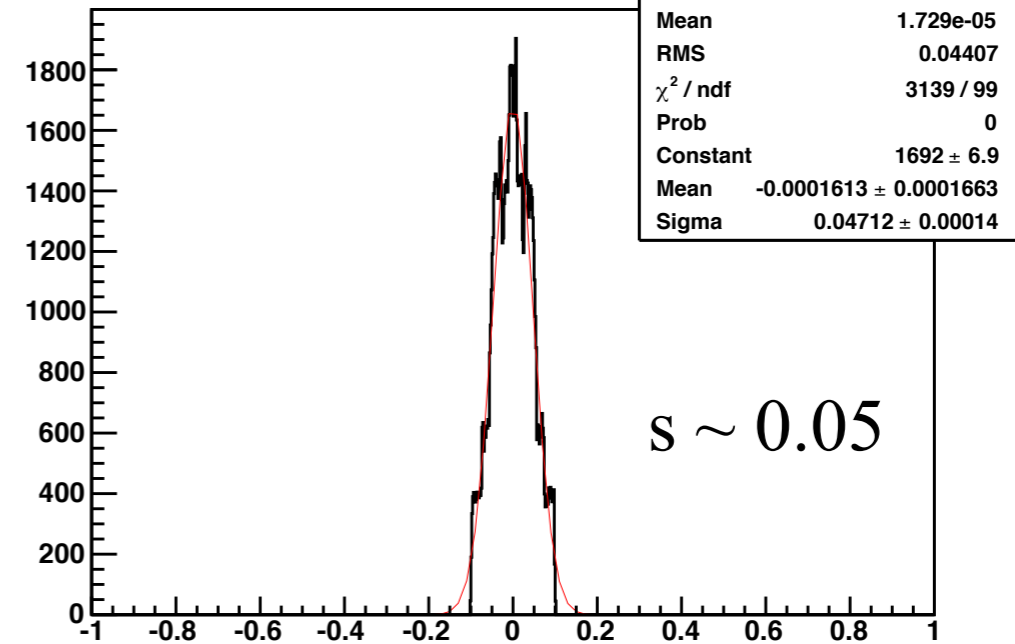
ADCのbit conversionの代わりに1/20 thre.のTOT conversionを入れてみた。

(pos. w/o noise) - (pos. w/ noise and/or bit conversion)

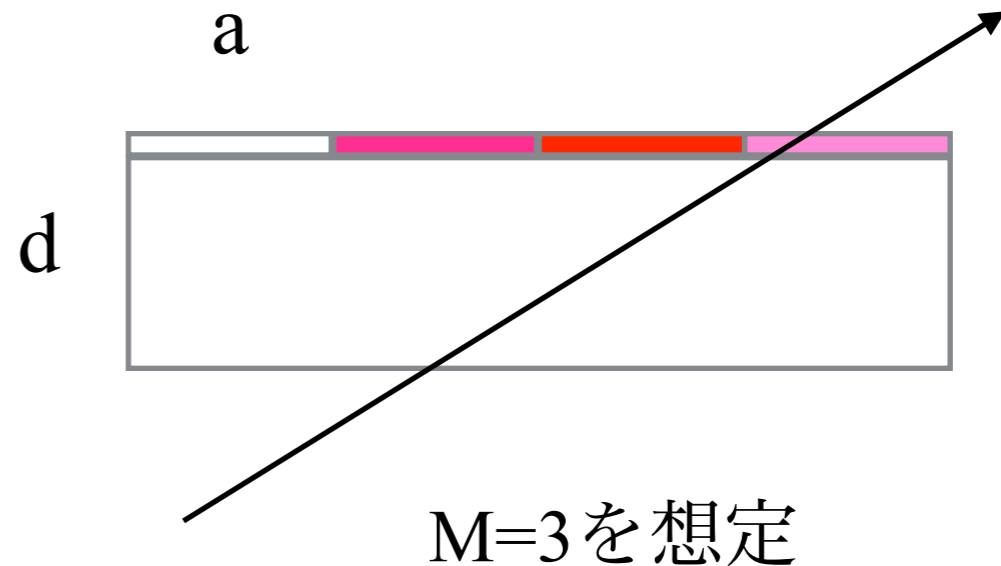
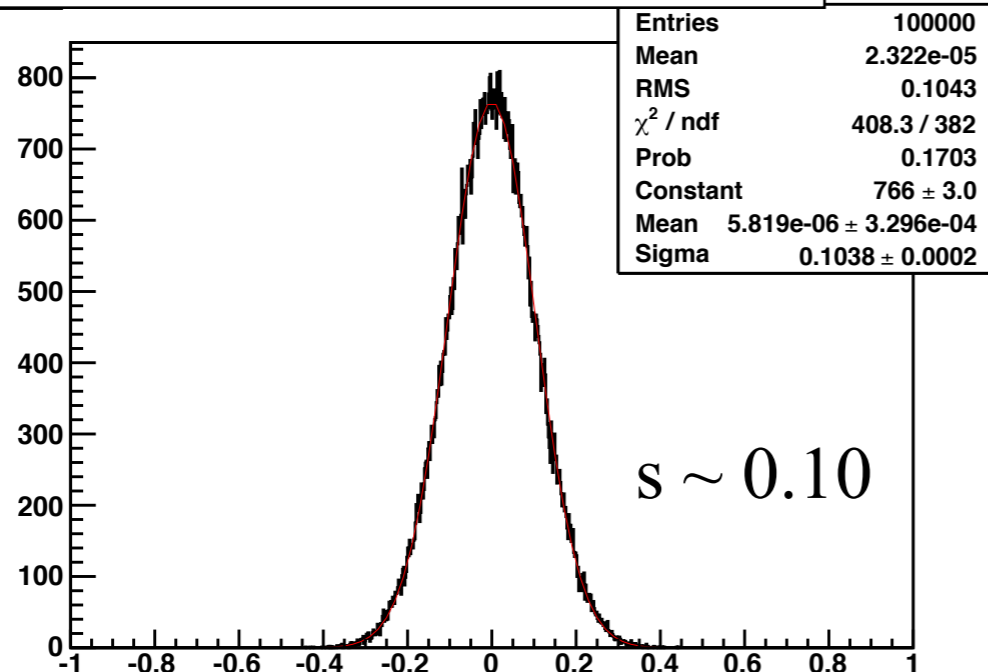
Noise only



TOT conversion only

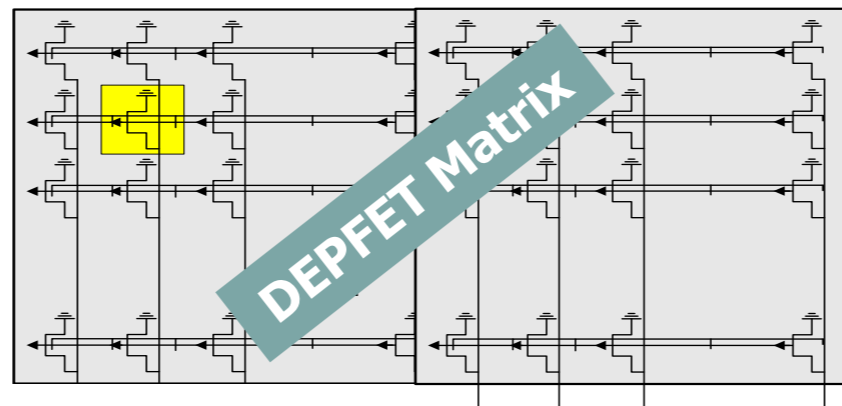
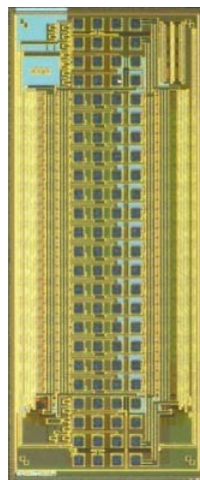


Noise + TOT conversion

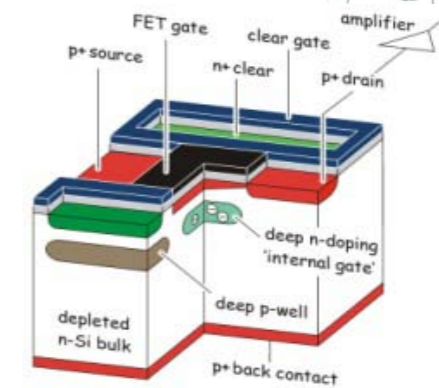


DEPFET and auxiliary ASICs

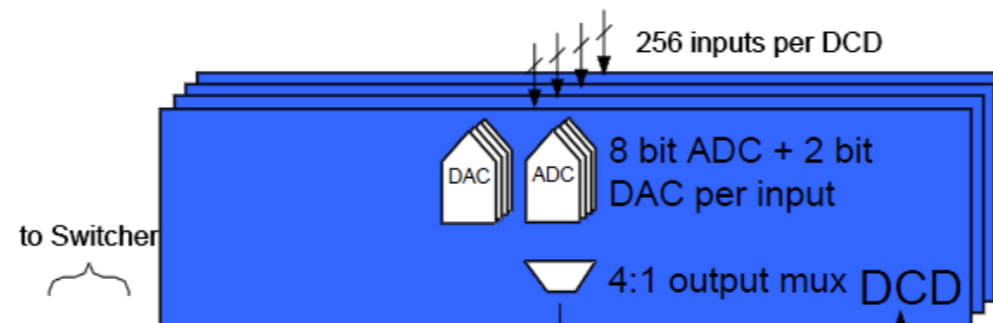
Switcher:
180nm HVCMOS AMS
Size $3.6 \times 1.5 \text{ mm}^2$
Gate and Clear signal
Fast HV up to 20V



10 MHz row frequency
100 ns ADC conversion time

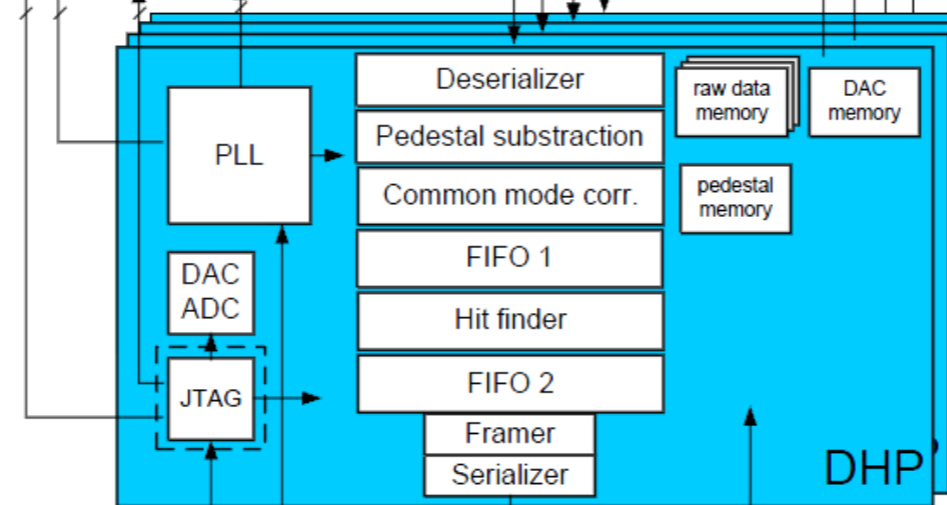


DCD:
"Drain Current Digitizer"
UMC 180nm
f/e and ADC



81.9 Gbps
320 Mbps output data x 256 lines

DHP:
"Data Handling Processor"
IBM 90nm → TSMC 65nm
Digital control chip



JTAG clock, sync one data out per DHP trigger

5 Gbps (1.25 Gbps link per DHP)

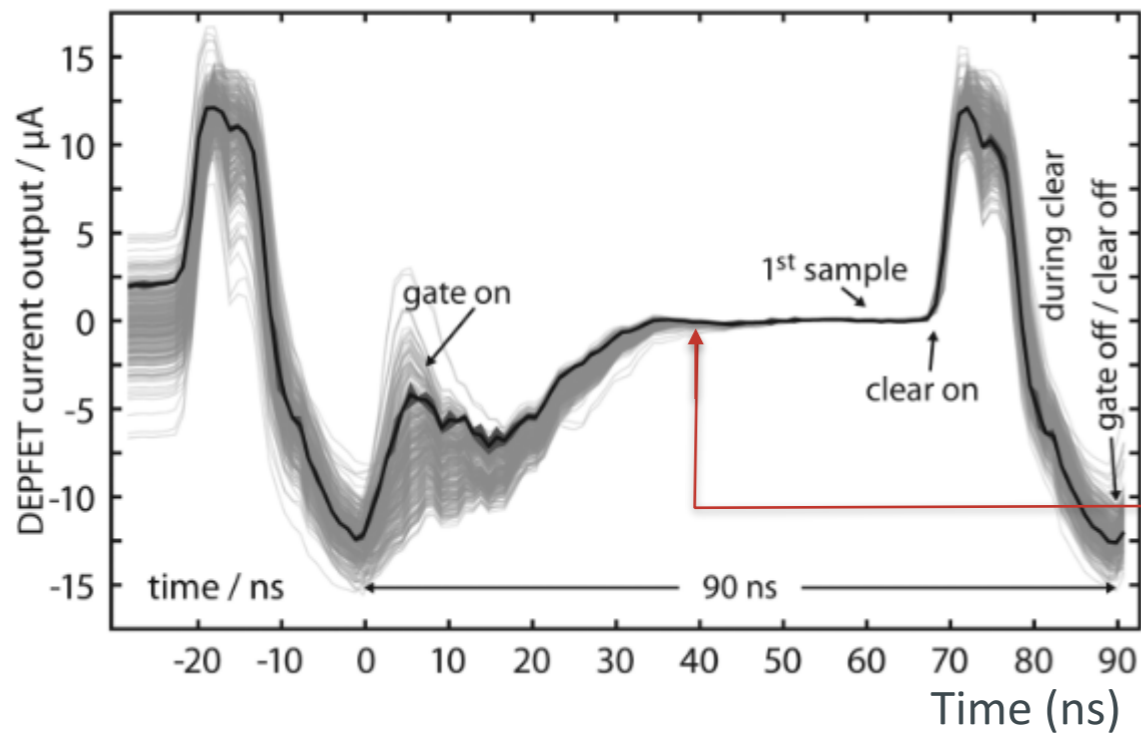
Power dissipation
DEPFETs ~ 1 W
Switcher ~ 1 W
DCD/DHP ~ 8 W on each ladder end

→ 160 W on each side of the detector
→ 40 W in sensitive volume

- CO₂ cooling at end flange
- gentle gas flow in sensitive region

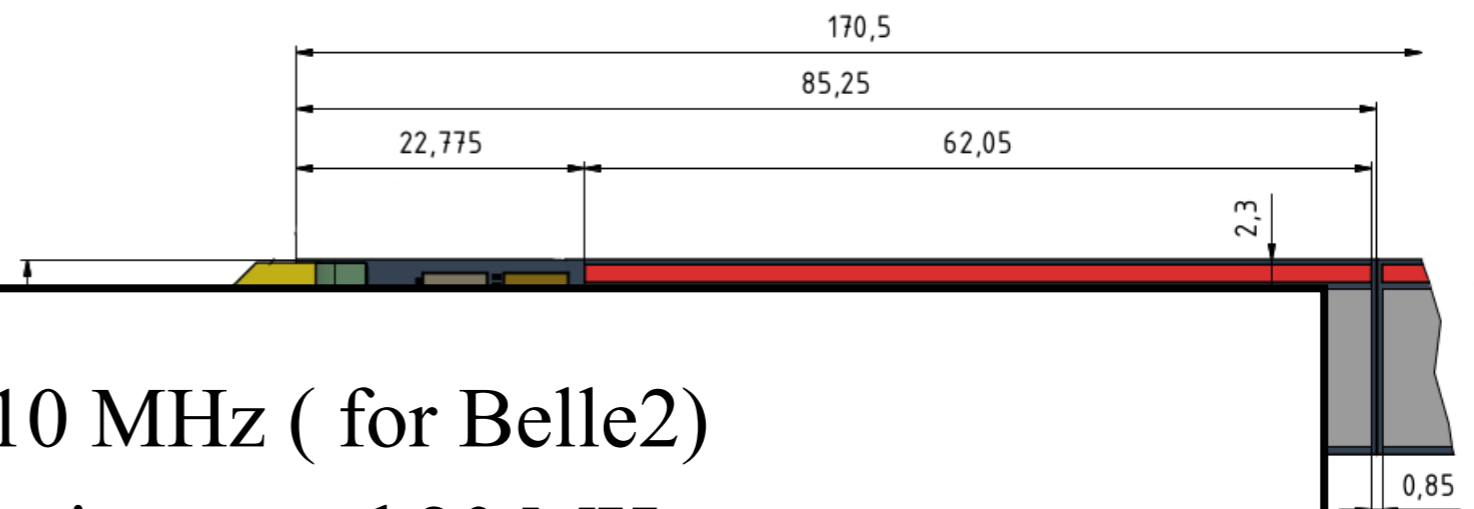
→ see Arantza's talk in R&D7, Thursday morning

Readout speed



Read-out speed: current state-of-the-art allows for a row rate of 1/100 ns. Room for improvement.

start to clear immediately drain current is stable reduce the time of read-out 30 ns



VXD0 read-o

Pixel si

Cent

$1 < |z|$

$|z| > 2 \text{ cm}$

- Row rate achieved 10 MHz (for Belle2)
- For ILC, it will be improved 20 MHz.
- By design, it can be achieved to be 40 MHz.

→ 25 x 100 μm²

Frame time: 40 μs (20 μs)